

ADMETA 2000 '00/10

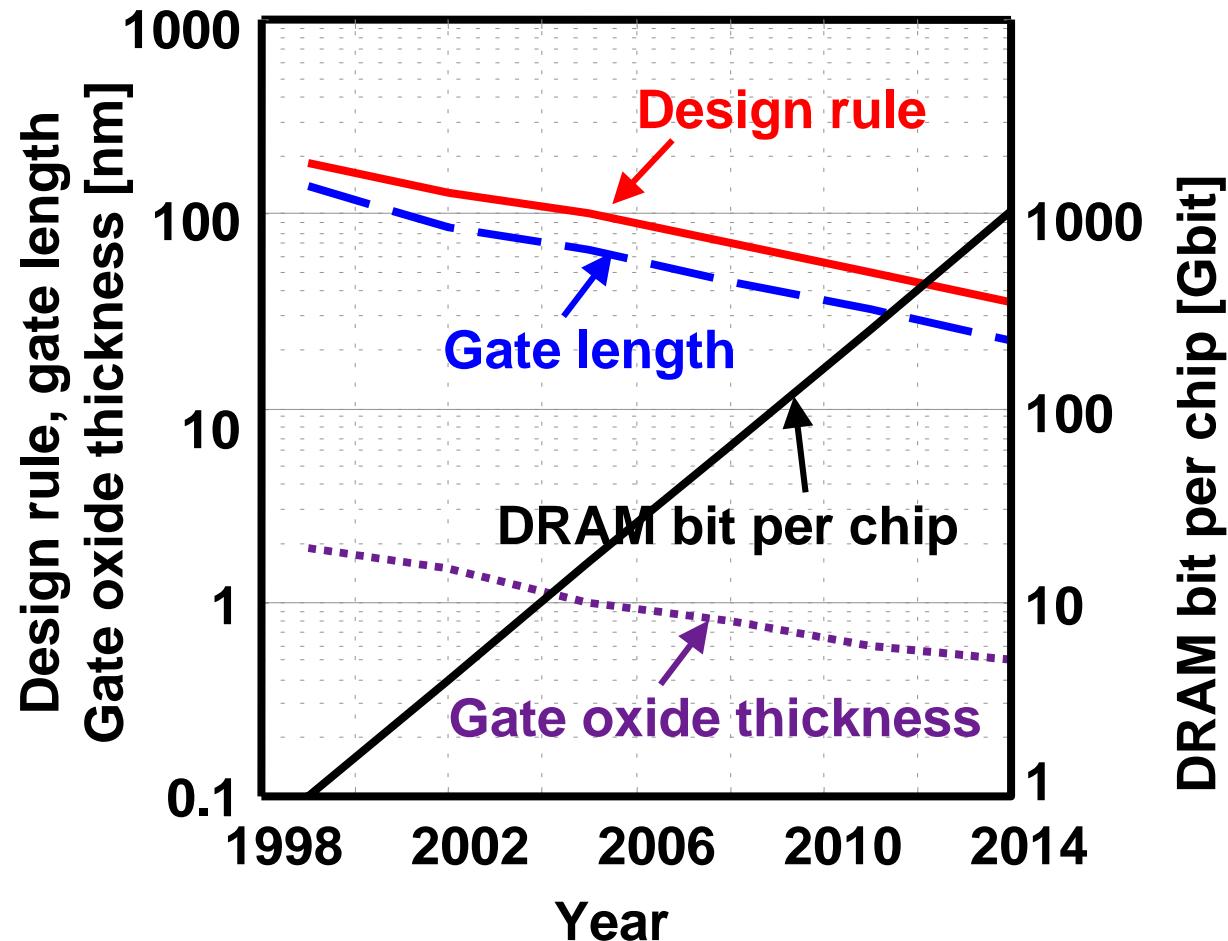
Interconnection from Design Perspective

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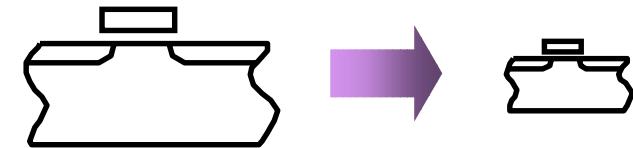
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<http://www.low-power.u-tokyo.ac.jp>**

Moore's Law



Scaling Law

| Transistors | | Scaling coefficients | |
|---------------------------------------|------------------------------|----------------------|-----------------------|
| | | 1/k | 1/k |
| V_{DD} | [V] | | |
| Tr. dimensions | [x] | 1/k | 1/k |
| Drain current | $[I \sim 1/x x/x V^{1.3}]$ | $1/k^{0.3}$ | |
| Gate capacitance | $[C \sim 1/x xx]$ | 1/k | |
| Tr. delay | $[d \sim CV/I]$ | $1/k^{1.7}$ | |
| Tr. power | $[P \sim VI \sim CVV/d]$ | $1/k^{1.3}$ | |
| Power density | $[p \sim P/x/x]$ | $k^{0.7}$ | |
| Tr. density | $[n \sim 1/x/x]$ | k^2 | |
| Interconnects | | | |
| Type | Scaling scenario | Local Scaled | Global Anti-scaled |
| Line thickness | [T] | 1/k | k |
| Width | [W] | 1/k | k |
| Separation | [S] | 1/k | k |
| Oxide thickness | [H] | 1/k | 1 |
| Length | [L] | 1/k | 1 |
| Resistance | $[R_{INT} \sim L/W/T]$ | k | $1/k^2$ |
| Capacitance | $[C_{INT} \sim LW/H]$ | 1/k | k |
| RC delay/Tr. delay | $[D \sim R_{INT} C_{INT}/d]$ | $k^{1.7}$ | — |
| Current density | $[J \sim pWL/V /W/T]$ | — | $k^{0.7}$ |
| DC noise / V_{DD} | $[N \sim JWTR/V]$ | — | $k^{1.7}$ |

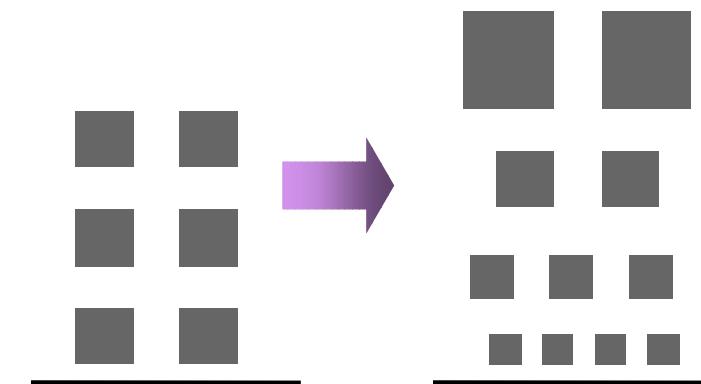


K=2

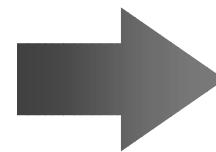
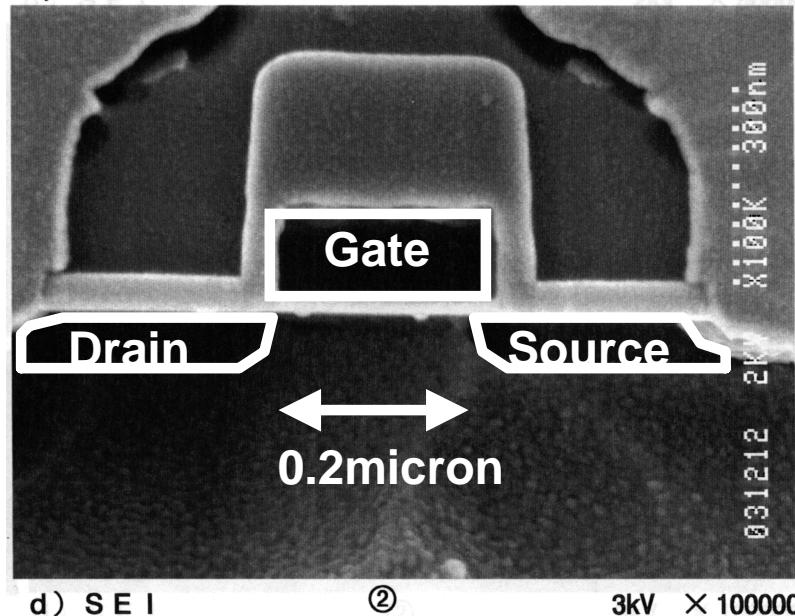
$$I_S = \frac{\mu \epsilon}{t_{ox}} \left(\frac{W}{L} \right) \frac{(V_{gs} - V_t)^\alpha}{2} \sim [V^\alpha / t]$$

$\alpha = 1.3$

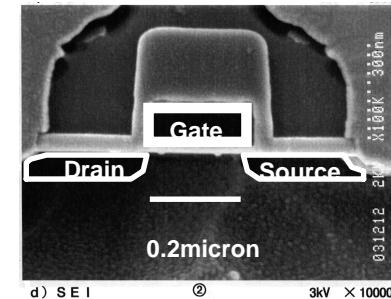
T.Sakurai&A.Newton,"Alpha-power law MOSFET model and its application to CMOS inverter delay and other formulas",IEEE JSSC, vol25, no,2, pp.584-594, Apr. 1990.



Scaling Law



Size 1/2



Favorable effects

| | |
|----------------|------|
| Size | x1/2 |
| Voltage | x1/2 |
| Electric Field | x1 |
| Speed | x3 |
| Cost | x1/4 |

Unfavorable effects

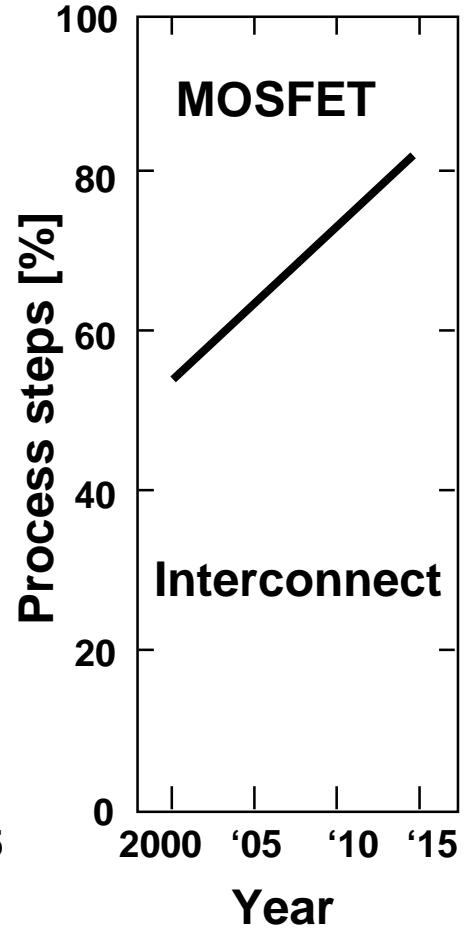
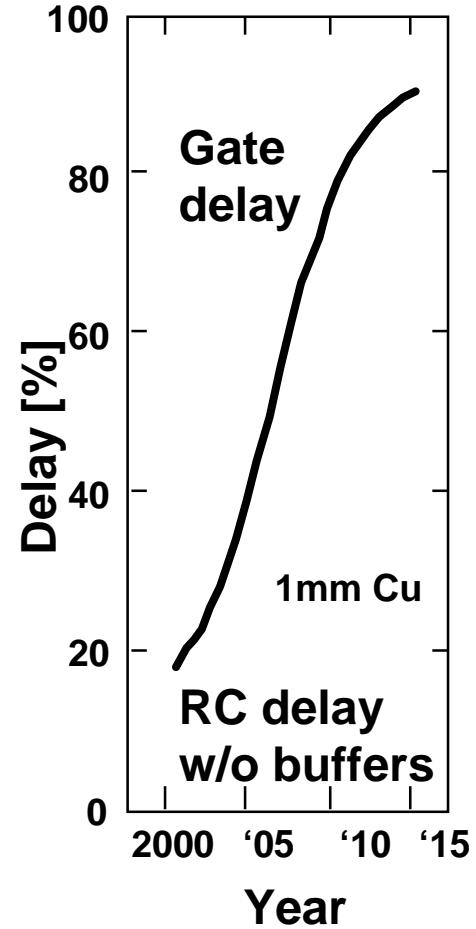
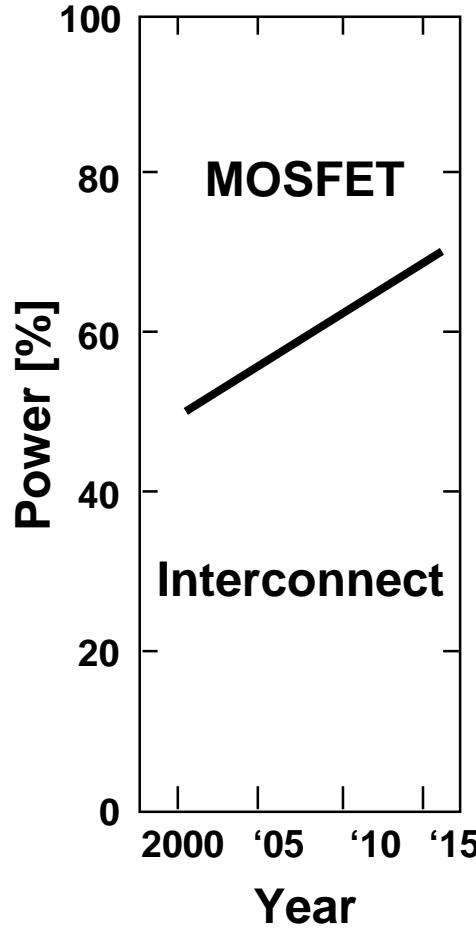
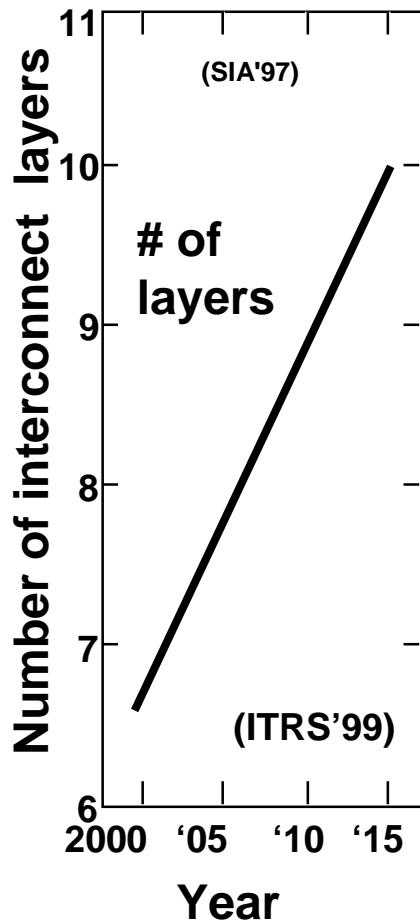
| | |
|--------------------|------|
| Power density | x1.6 |
| RC delay/Tr. delay | x3.2 |
| Current density | x1.6 |
| Voltage noise | x3.2 |
| Design complexity | x4 |

Three crises in VLSI designs

- **Power crisis**
- **Interconnection crisis**
- **Complexity crisis**

Interconnect determines cost & perf.

P: Power, D: Delay, A: Area, T:Turn-around



DSM interconnect design issues

Larger current

- IR drop (static and dynamic)**
- Reliability (electro-migration)**

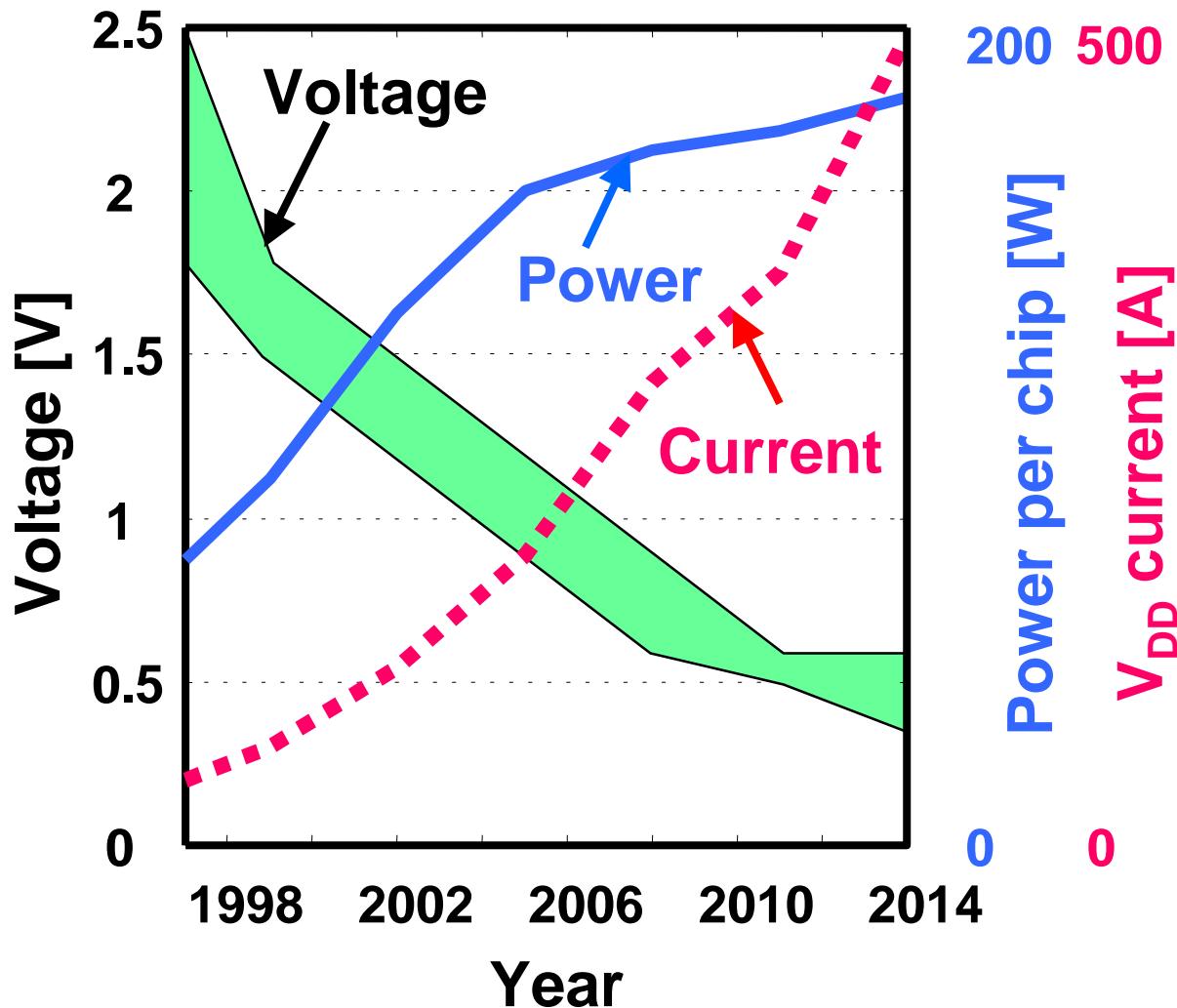
Smaller geometry / Denser pattern

- RC delay**
- Signal Integrity**
- Crosstalk noise**
- Delay fluctuation**

Higher speed

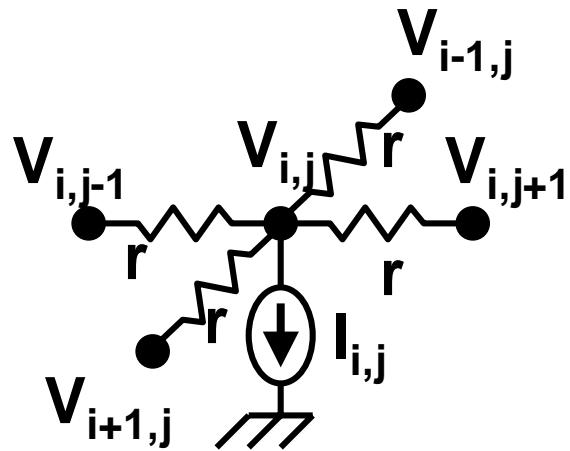
- Inductance**
- EMI**

VDD, Power and Current Trend

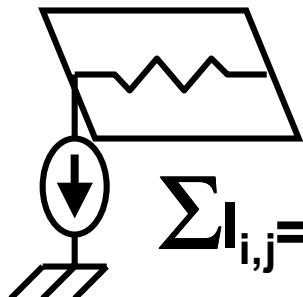


International Technology Roadmap for Semiconductors 1998 update sponsored by the Semiconductor Industry Association in cooperation with European Electronic Component Association (EECA), Electronic Industries Association of Japan (EIAJ), Korea Semiconductor Industry Association (KSIA), and Taiwan Semiconductor Industry Association (TSIA)

IR Drop

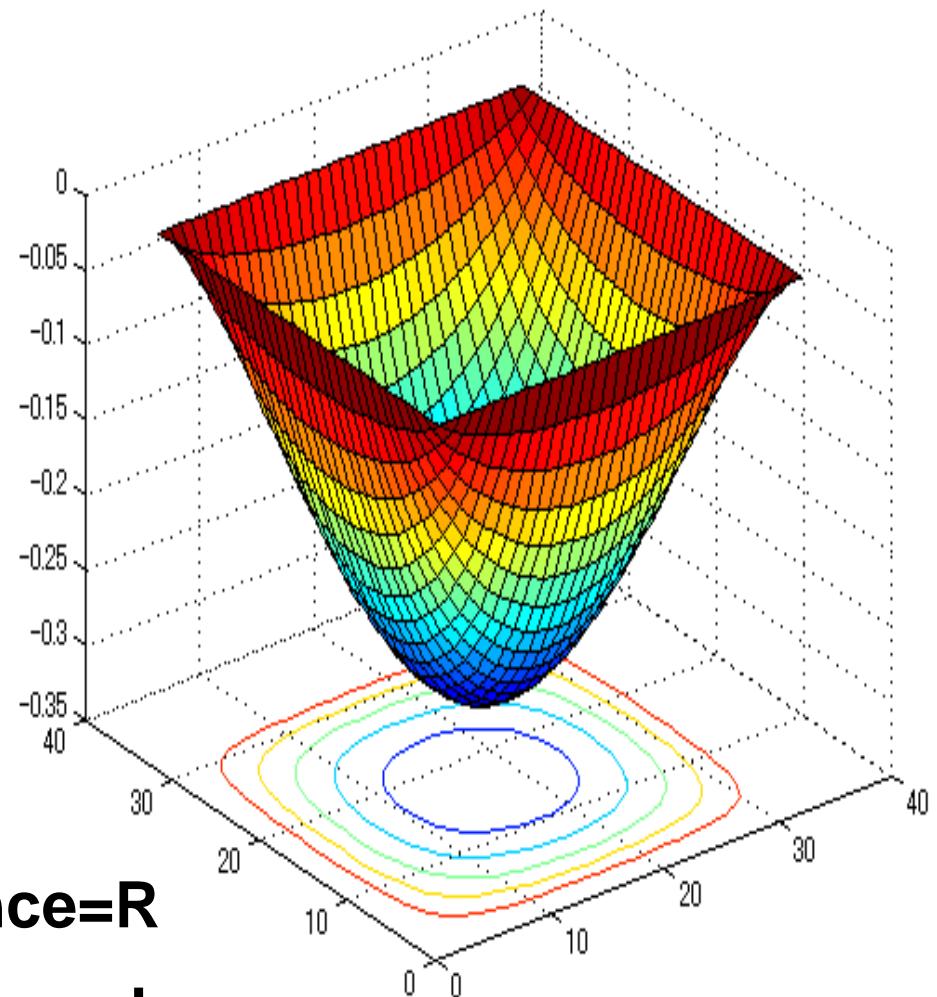


$$V_{i,j} = (V_{i-1,j} + V_{i+1,j} + V_{i,j-1} + V_{i,j+1})/4 - r I_{i,j}$$



$\sum I_{i,j} = I$, Sheet resistance = R

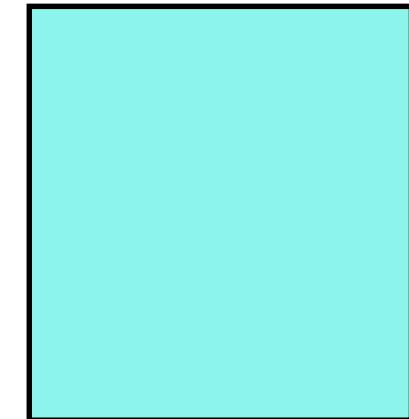
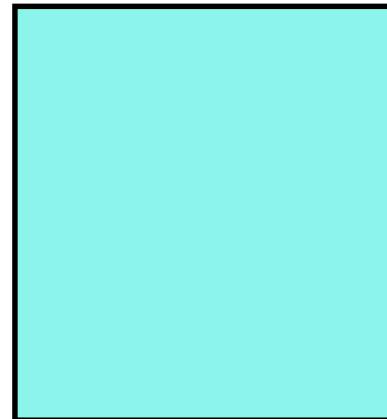
Take IR as unity voltage drop



Interconnect Cross-Section and Noise

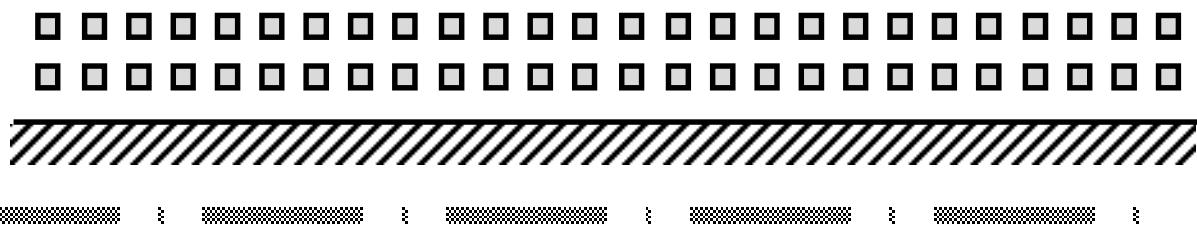
Unscaled / anti-scaled

- Clock
- Long bus
- Power supply



Scaled interconnect

- Signal

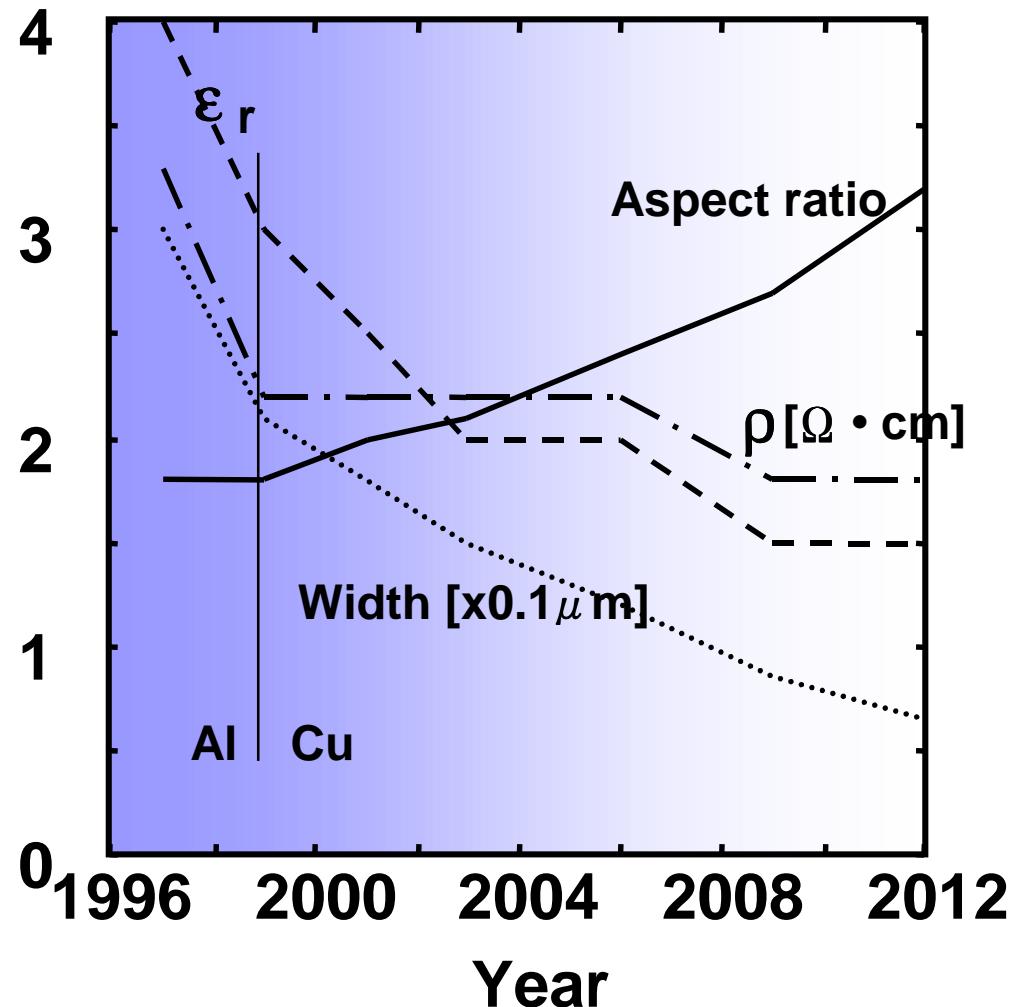


1V 20W → 20A current

2% noise on VDD & VSS → ~0.02V / 20A → ~10µm thick Cu

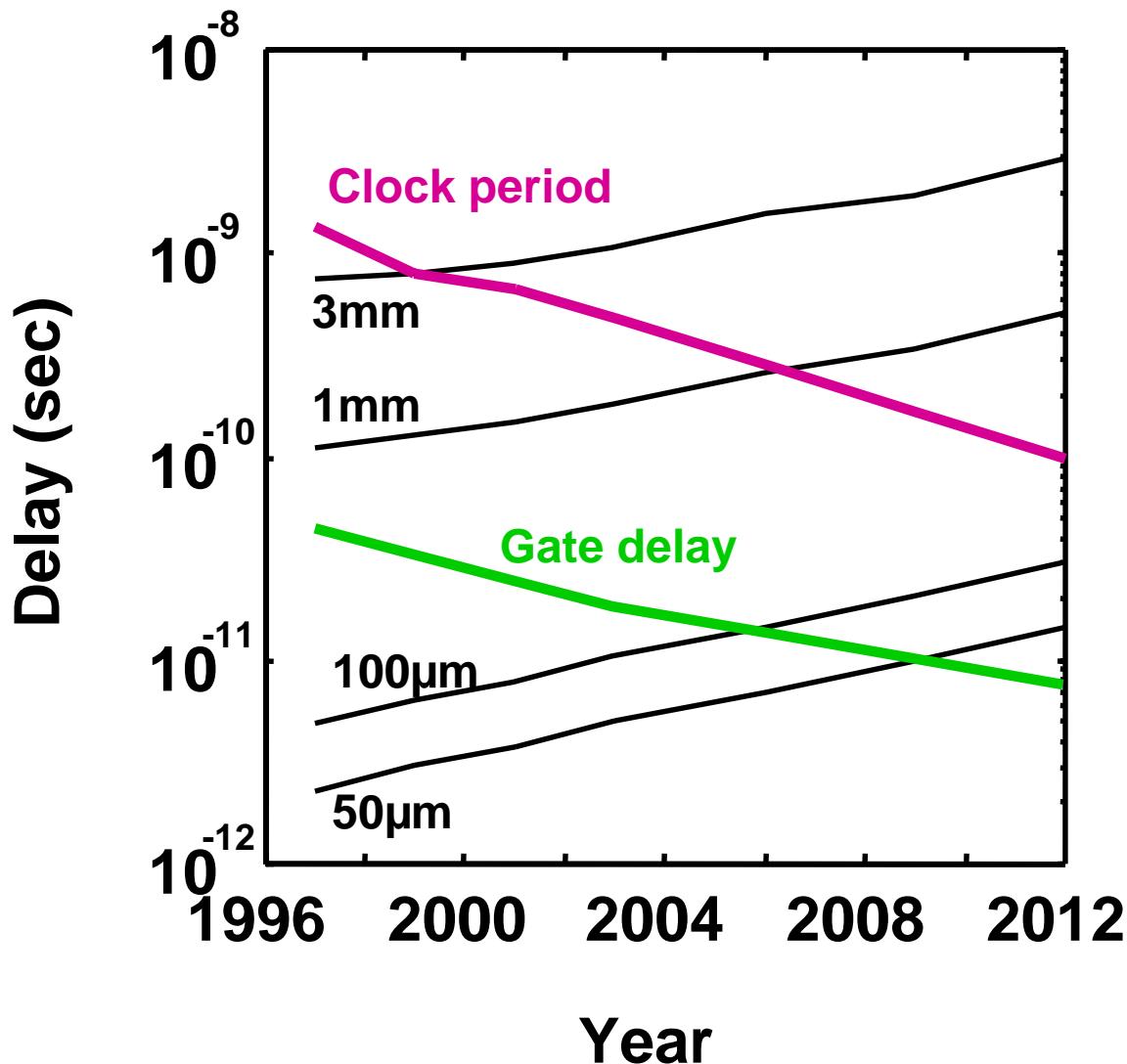
Thick layer interconnect, area pad, package are co-designed.

Interconnect parameters trend

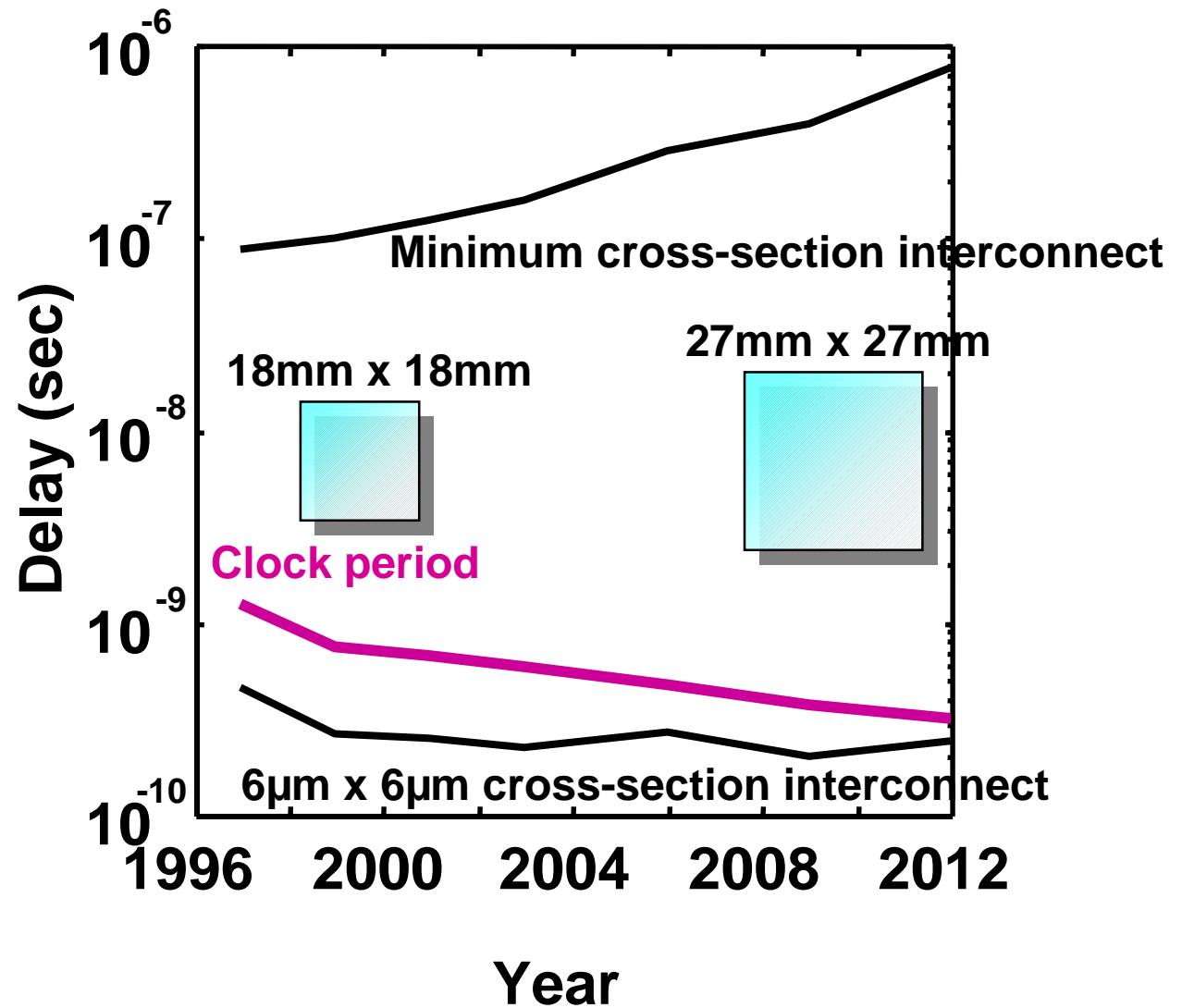
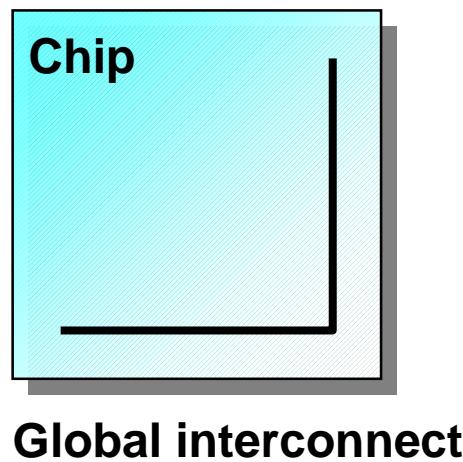


Semiconductor Industry Association roadmap
<http://notes.sematech.org/1997pub.htm>

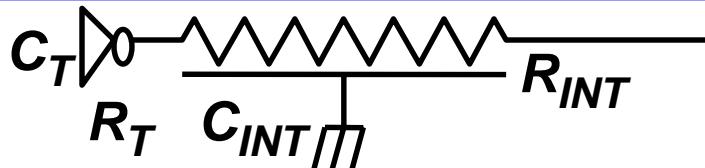
RC delay and gate delay



RC delay of global interconnections

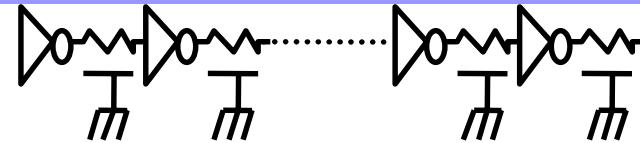


Repeaters



a) Without repeaters

$$t_{05} \approx 0.377R_{INT}C_{INT} + 0.693(R_T C_T + R_T C_{INT} + R_{INT} C_T)$$



b) With repeaters

C_0 : Gate capacitance of minimum MOSFET

R_0 : Gate effective resistance of minimum MOSFET

$$\text{Delay} \approx k \left[p_1 \frac{R_{INT}}{k} \frac{C_{INT}}{k} + p_2 \left(\frac{R_0}{h} h C_0 + \frac{R_0}{h} \frac{C_{INT}}{k} + \frac{R_{INT}}{k} h C_0 \right) \right] : \text{Buffered}$$

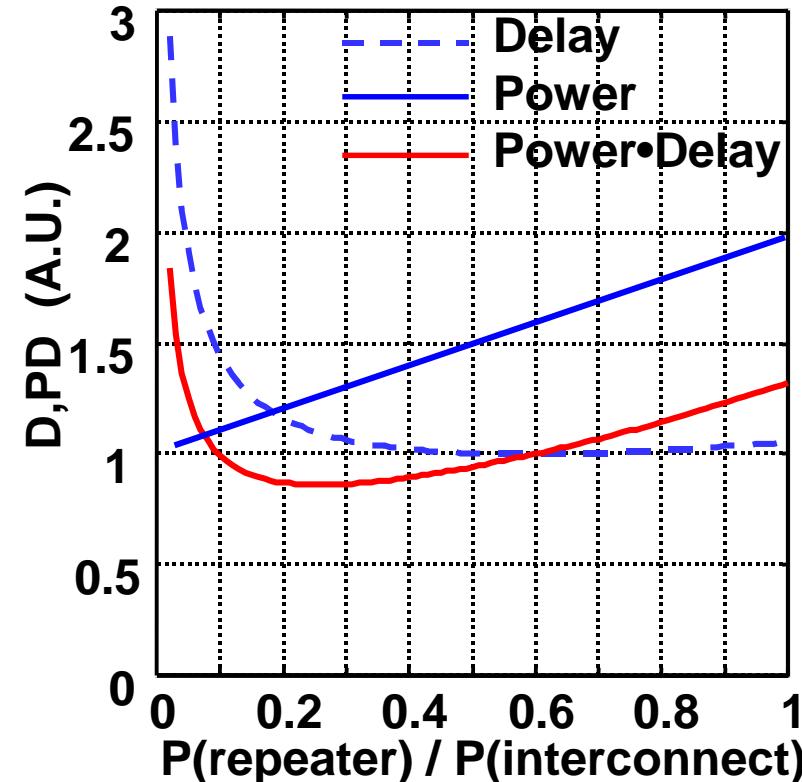
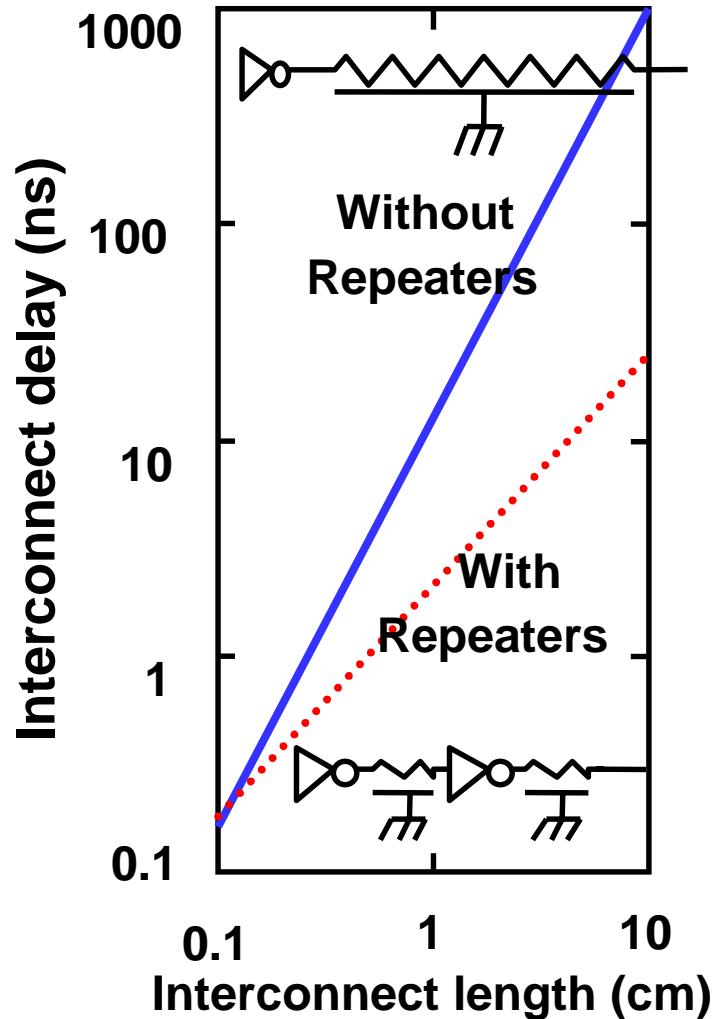
$$\frac{\partial \text{Delay}}{\partial h} = 0 \rightarrow h_{OPT} = \sqrt{\frac{C_{INT} R_0}{R_{INT} C_0}} : \text{Optimized size of buffer inverter}$$

$$\frac{\partial \text{Delay}}{\partial k} = 0 \rightarrow k_{OPT} = \sqrt{\frac{p_1}{p_2}} \sqrt{\frac{R_{INT} C_{INT}}{R_0 C_0}} : \text{Optimized number of stages}$$

$$\text{Delay}_{OPT} = 2 \left(\sqrt{p_1 p_2} + p_2 \right) \sqrt{R_{INT} C_{INT} R_0 C_0} \approx 2.4 \sqrt{\tau_{INT} \tau_{MOS}}$$

$$\text{Cap. of gates} = k_{OPT} h_{OPT} C_0 = \sqrt{p_1 / p_2} C_{INT} = 0.73 C_{INT}$$

Delay and Power Optimization for Repeaters



Delay optimized

→P: $P(\text{repeater})=0.60 P(\text{interconnect})$

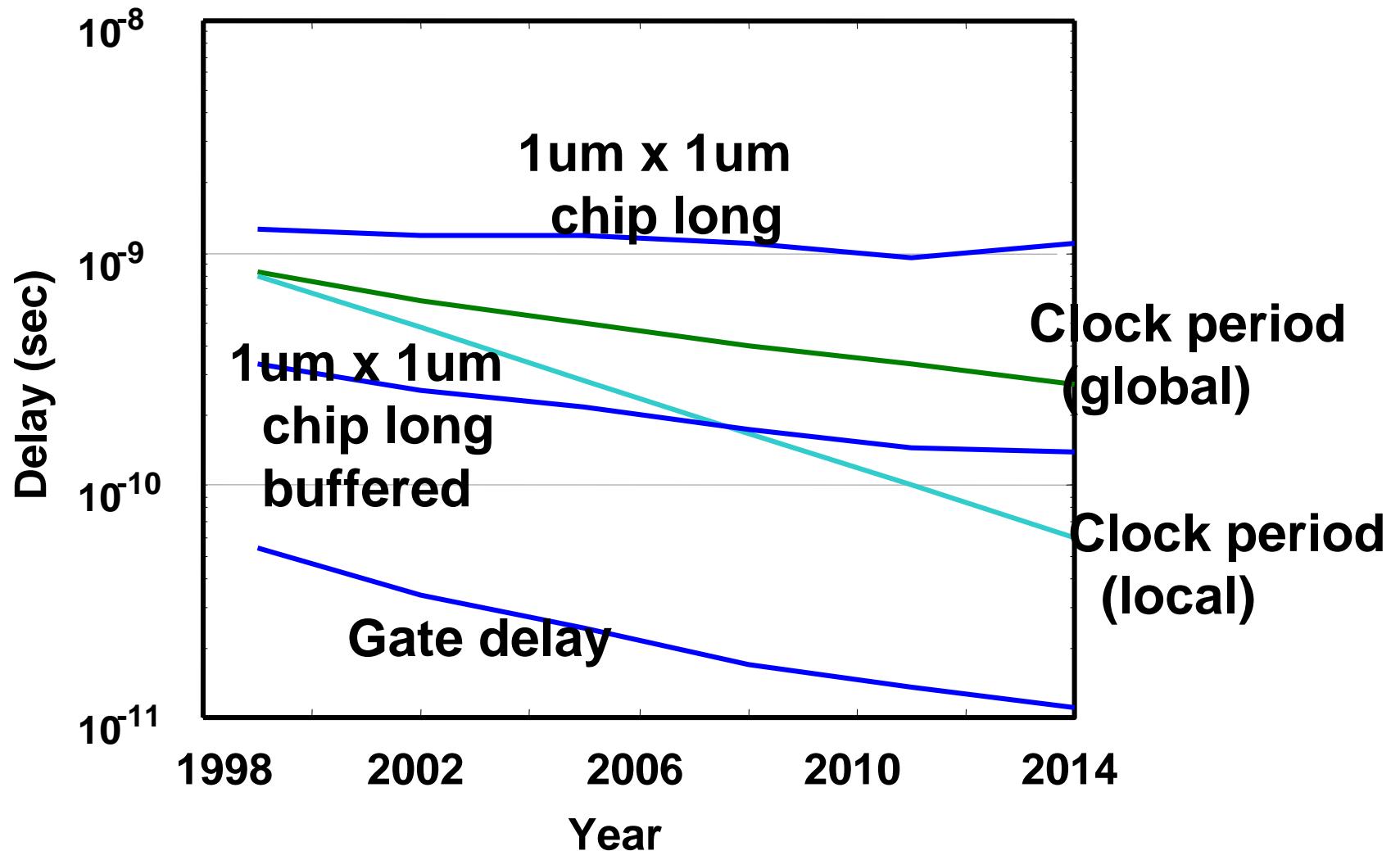
Power•Delay optimized

→D: 1.09 D_{opt}

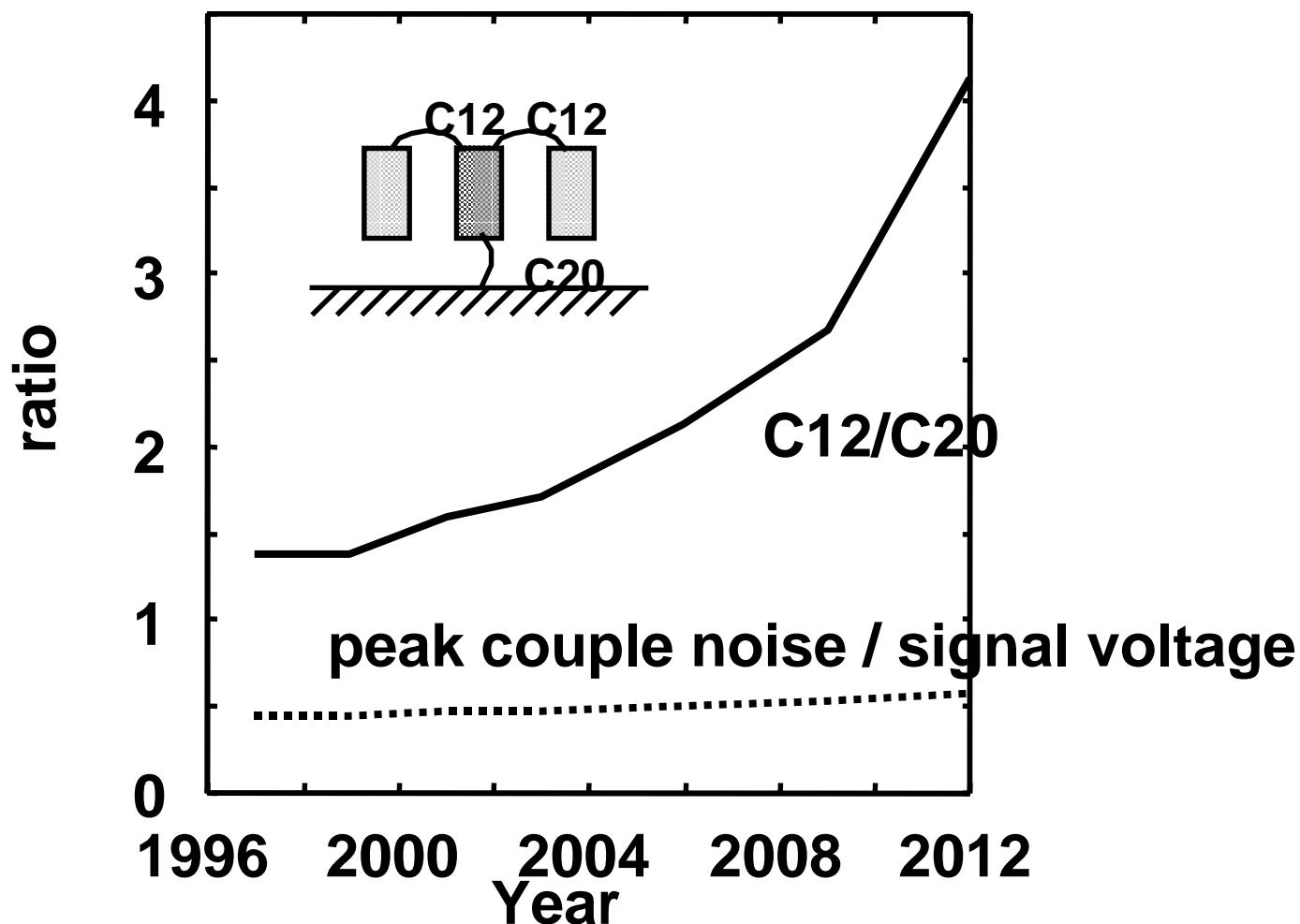
→P: $P(\text{repeater})=0.26 P(\text{interconnect})$

→PD: 0.86 of D_{opt} case

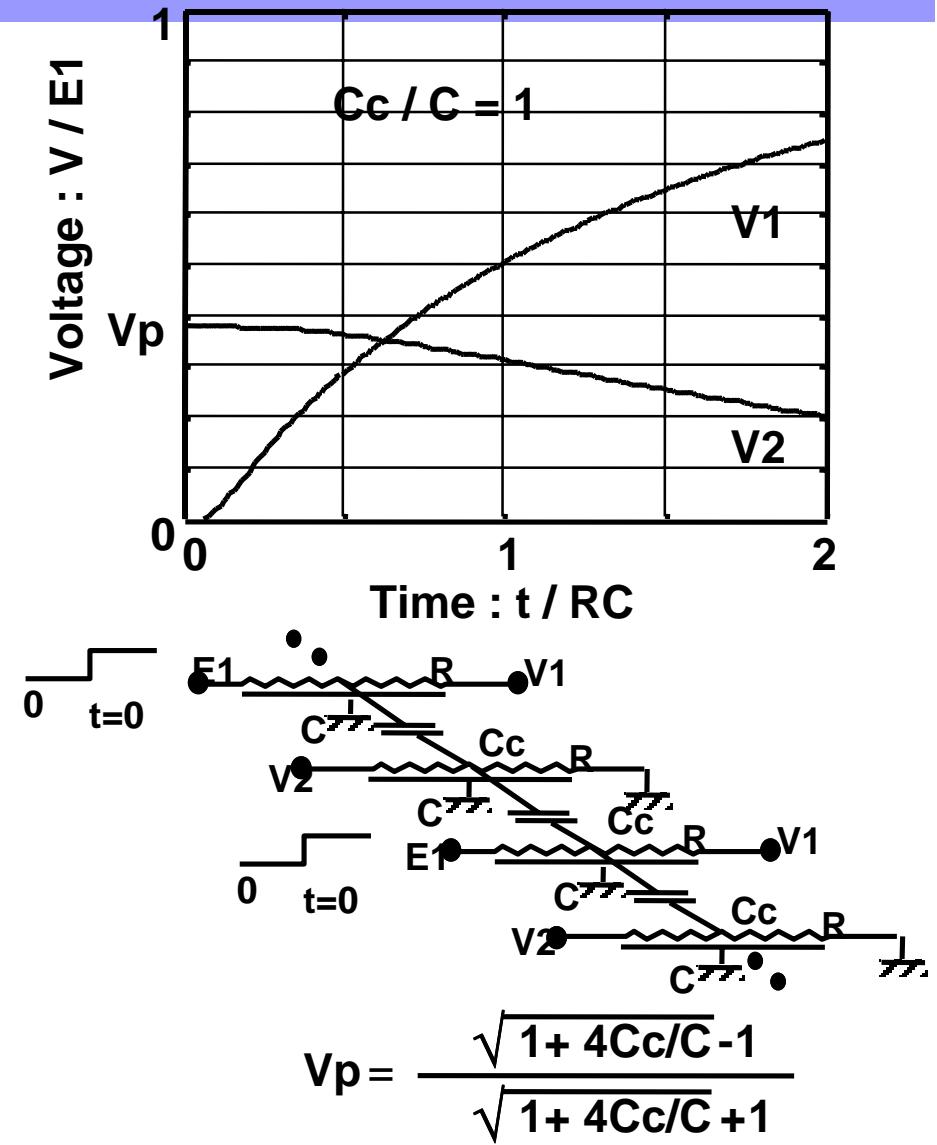
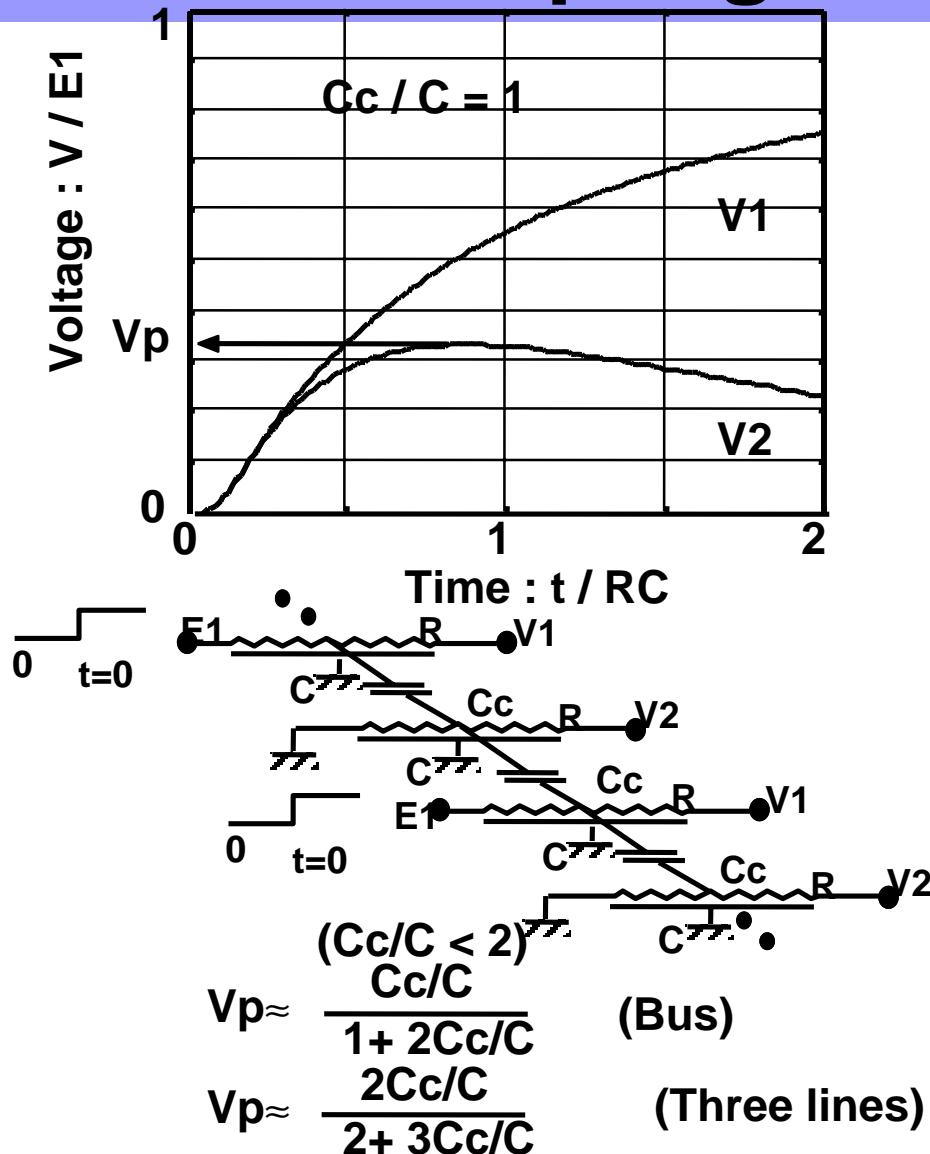
Buffered interconnect delay



Capacitive Coupling Noise

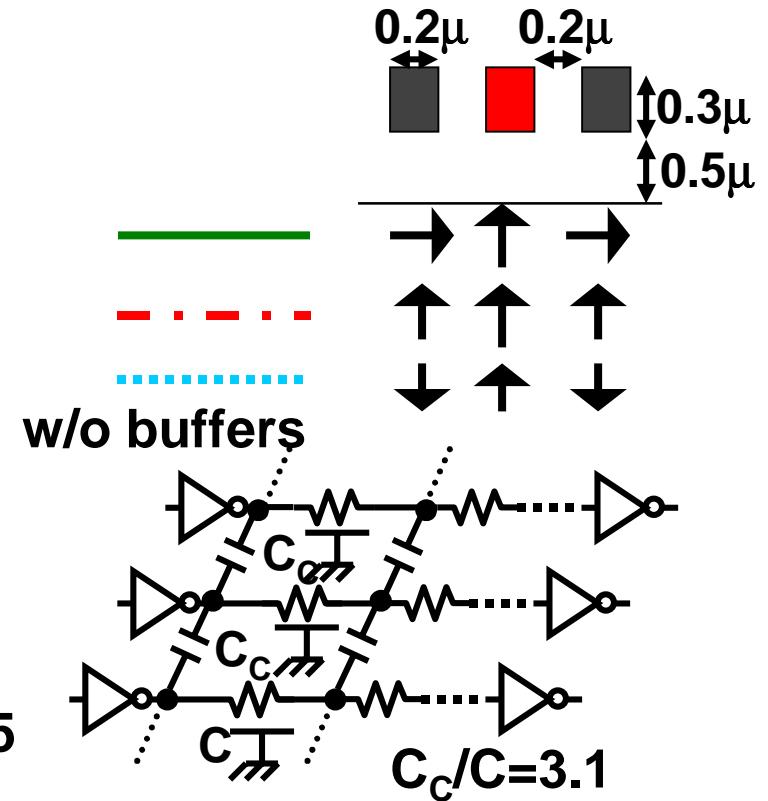
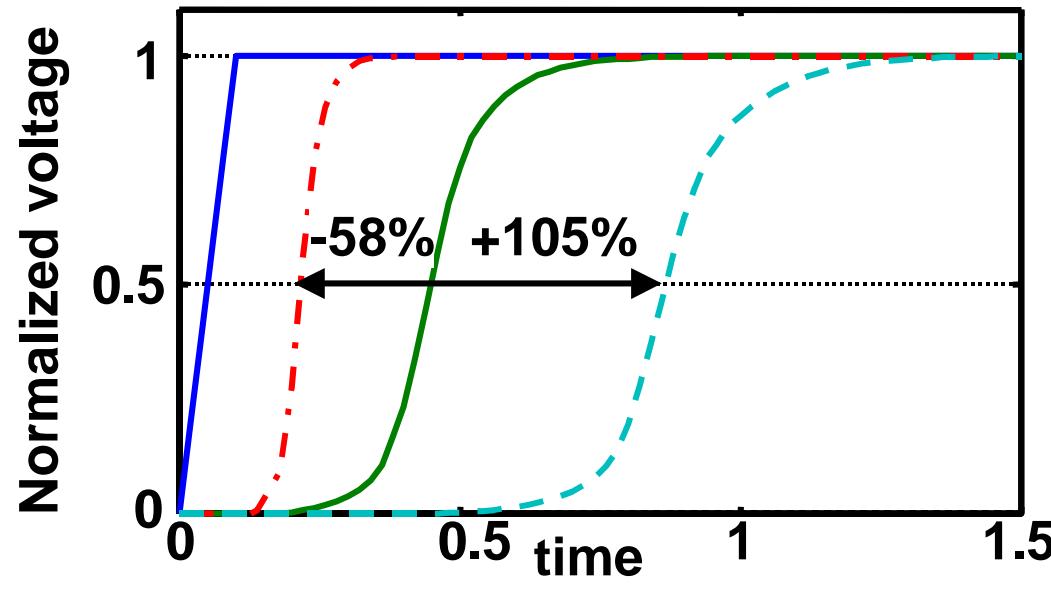


Coupling noise in RC bus



H.Kawaguchi and T.Sakurai, "Delay and Noise Formulas for Capacitively Coupled Distributed RC Lines," ASPDAC, Digest of Tech. Papers, pp.35-43, Feb. 1998.

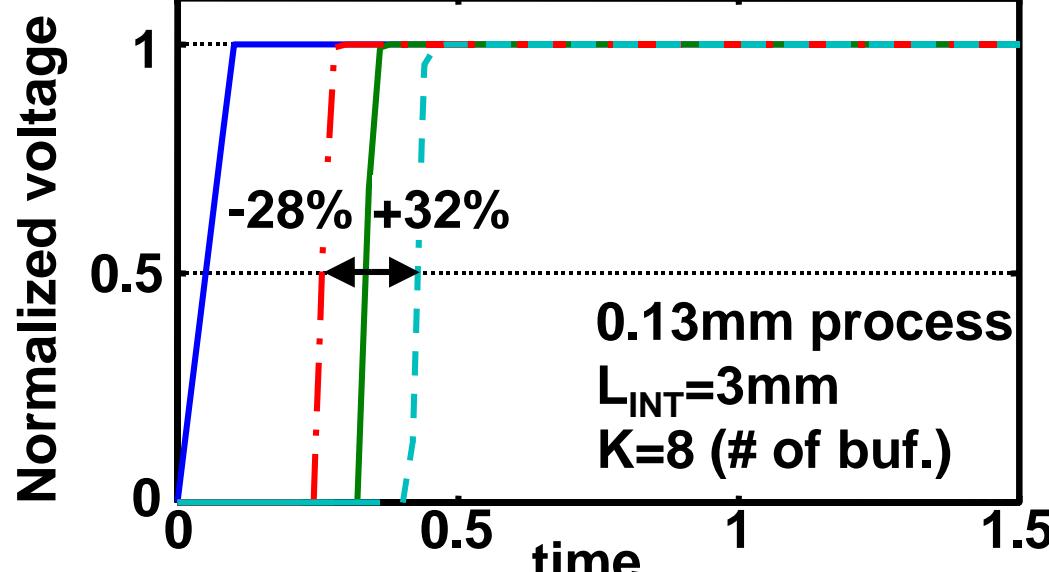
Coupling among Interconnections



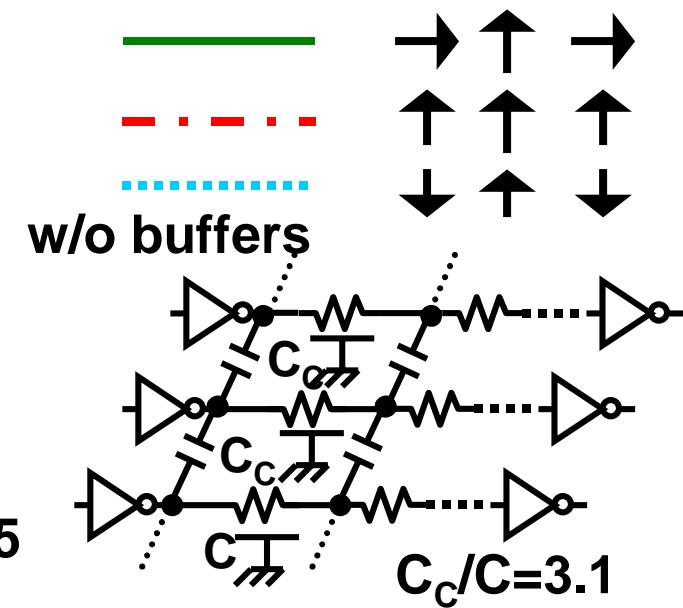
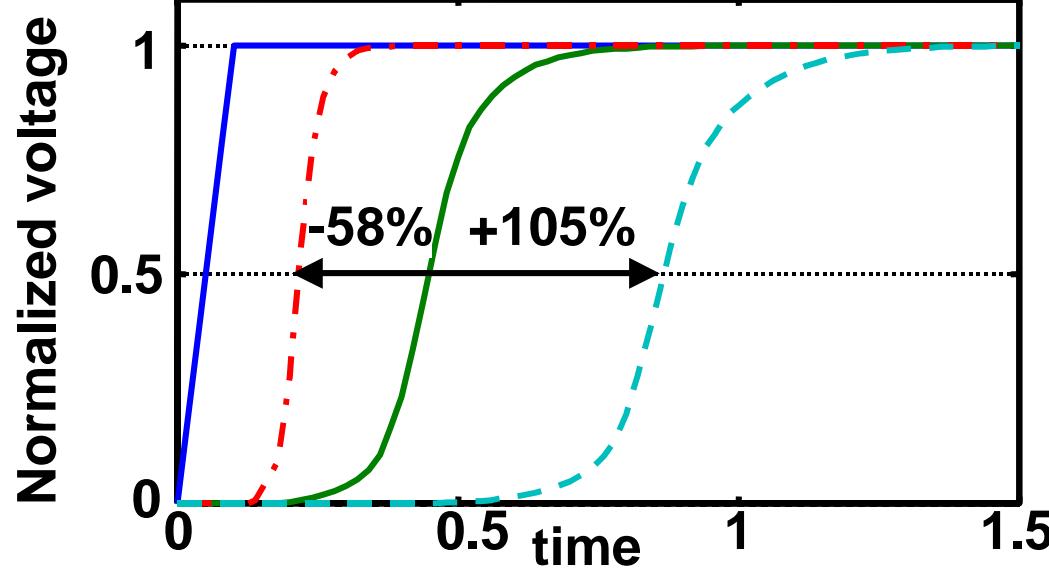
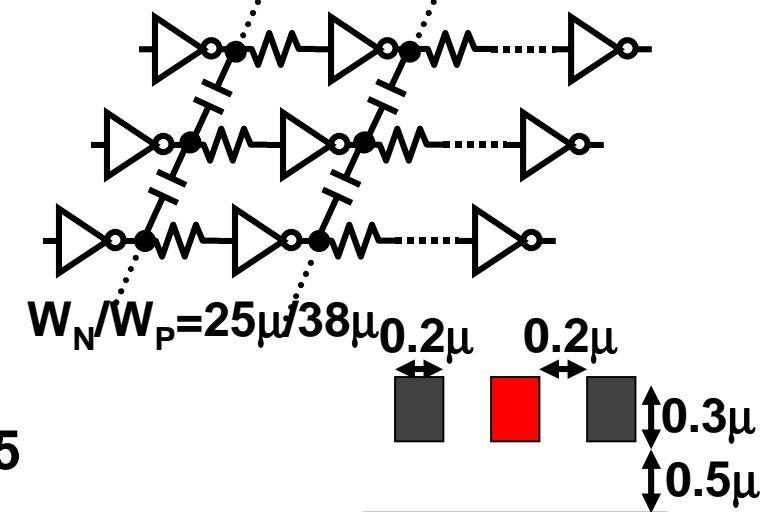
$$\frac{t_{pd}}{RC} = \frac{1}{2} + 2\eta - \frac{1}{\sqrt{6}} \log \frac{e}{2} \sqrt{1 + 8\eta + 6\eta^2}$$
$$\approx 1.63\eta + 0.37 (\eta \leq 2) \quad (\eta = C_C / C)$$

H.Kawaguchi and T.Sakurai, "Delay and Noise Formulas for Capacitively Coupled Distributed RC Lines," 1998 ASPDAC, Digest of Tech. Papers, pp.35-43, Feb. 1998.

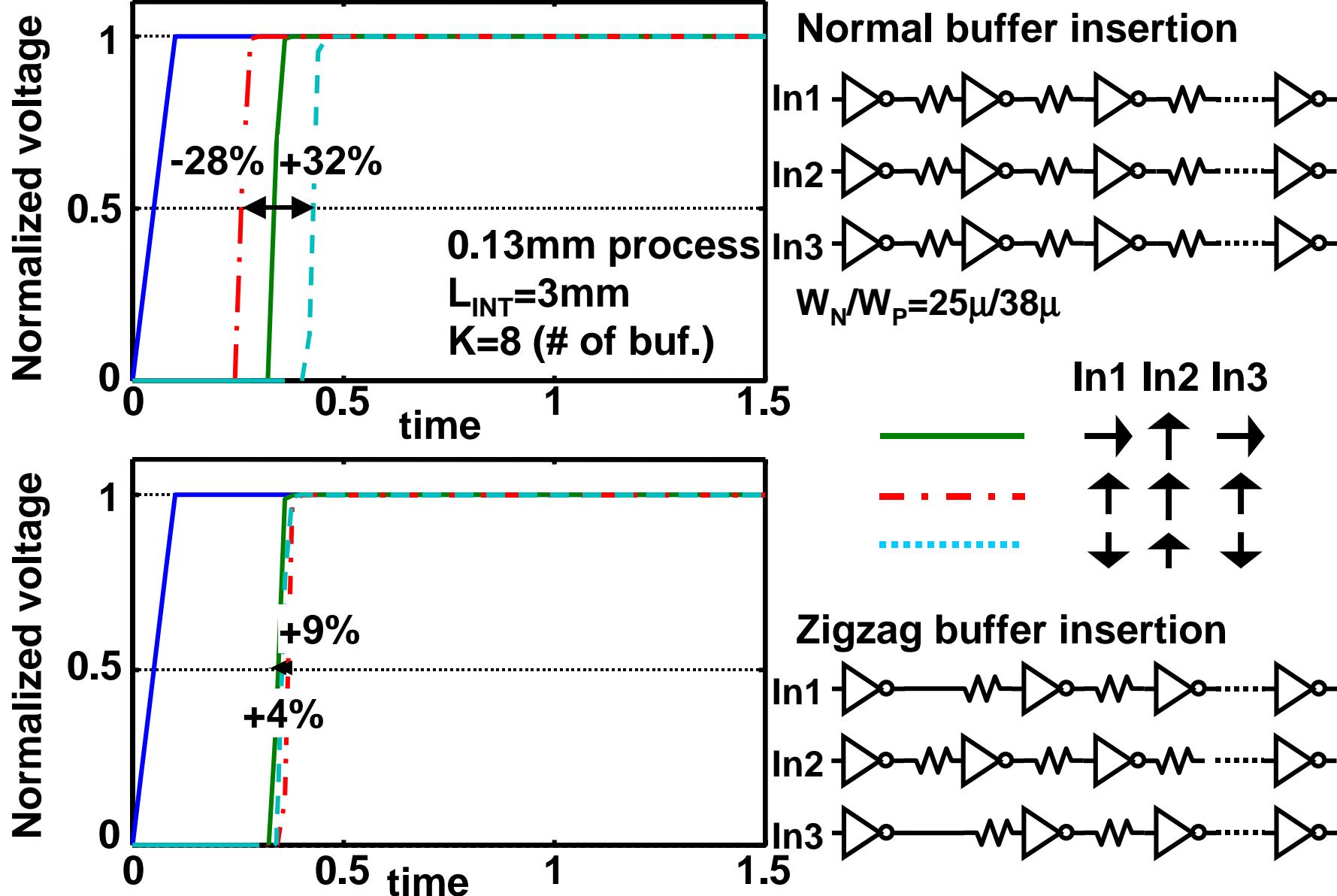
Coupling among Interconnections



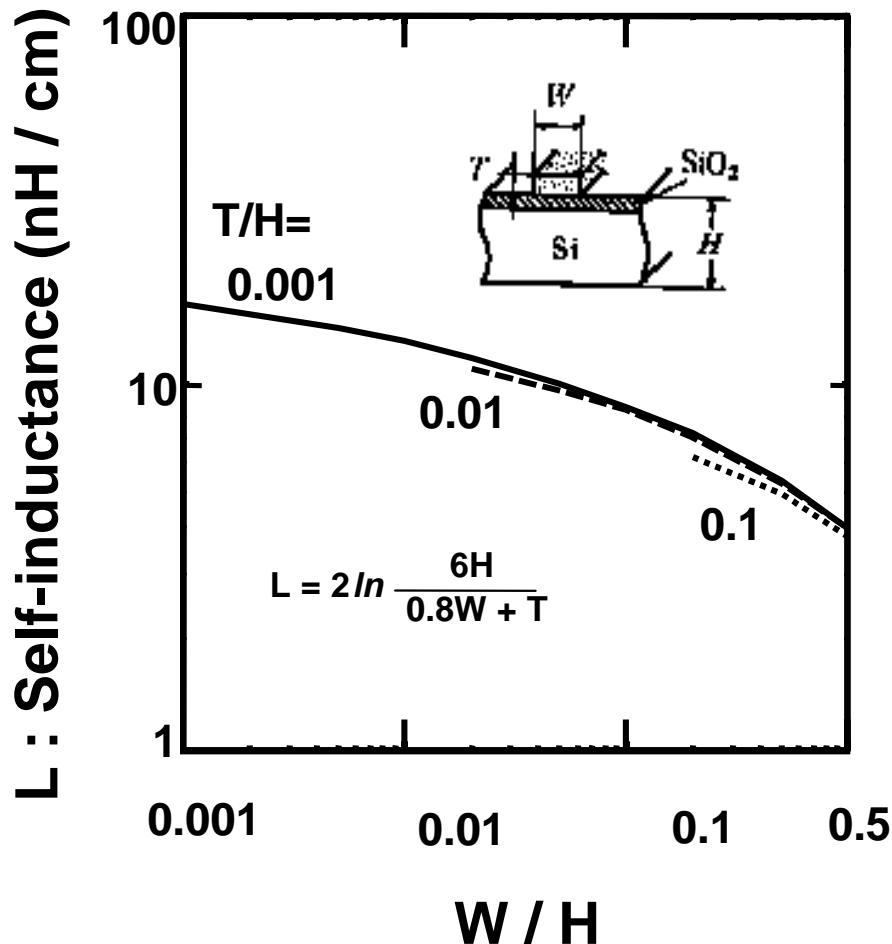
Optimized buffer insertion



Coupling among Interconnections



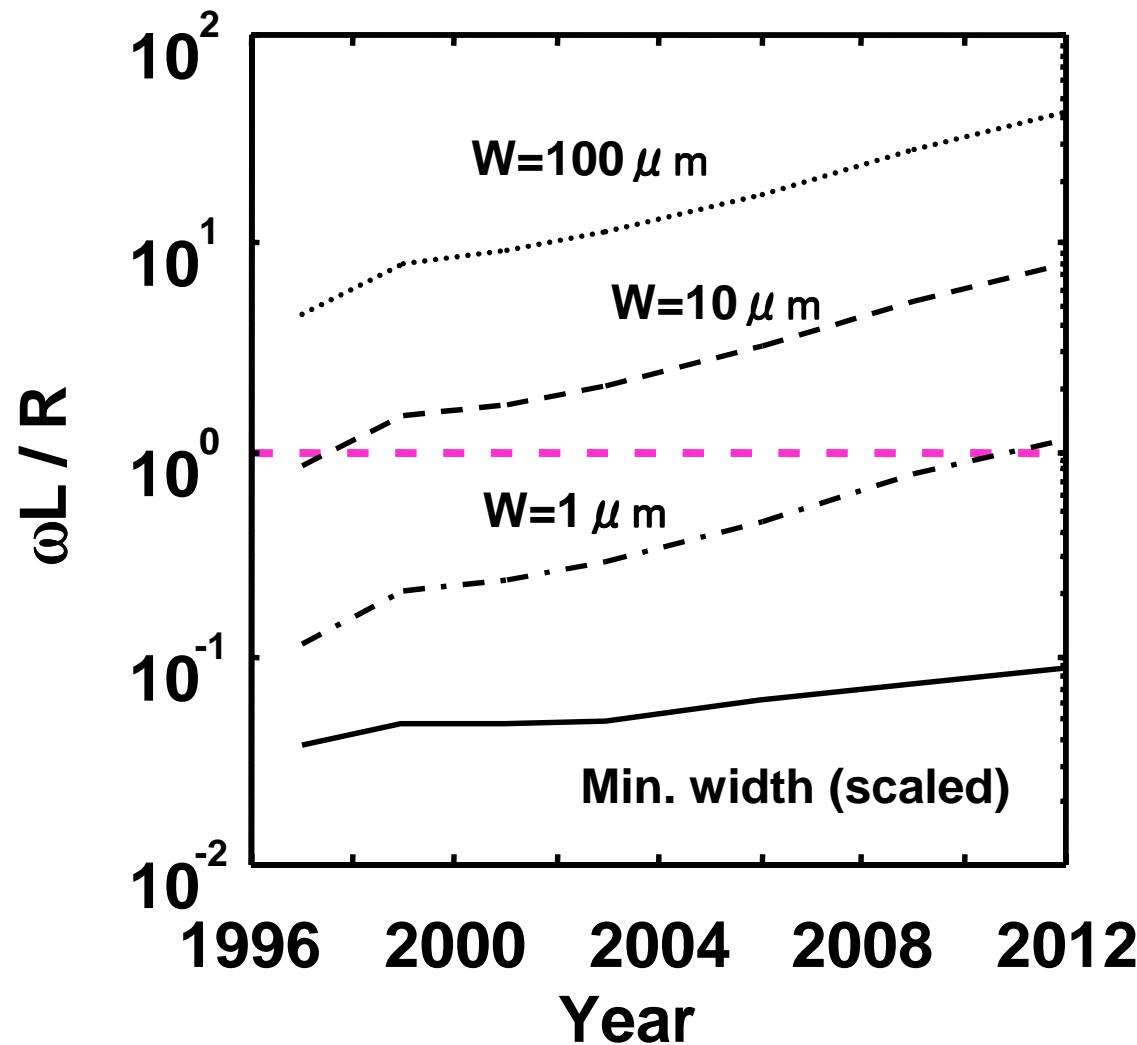
Inductance?



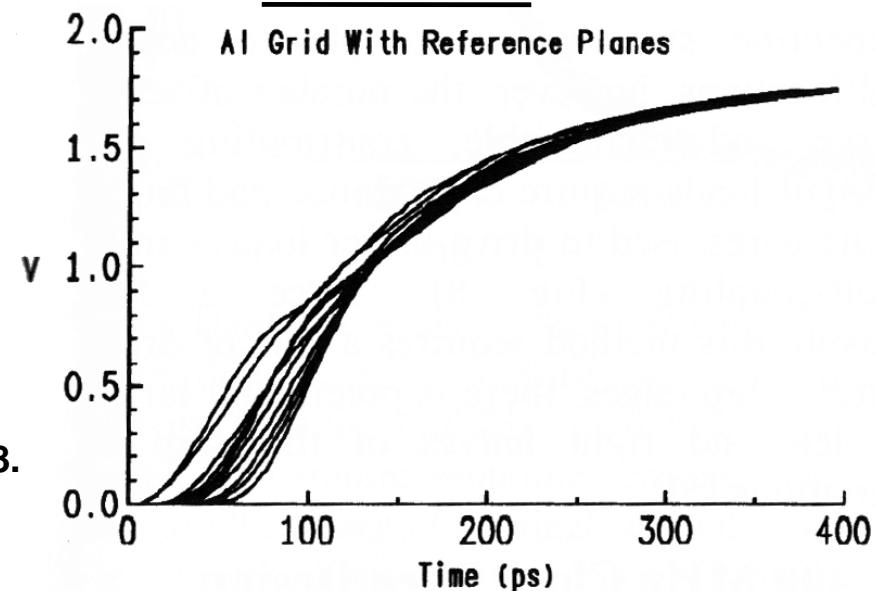
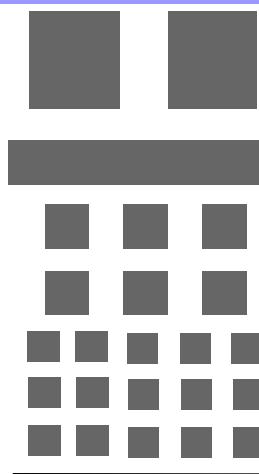
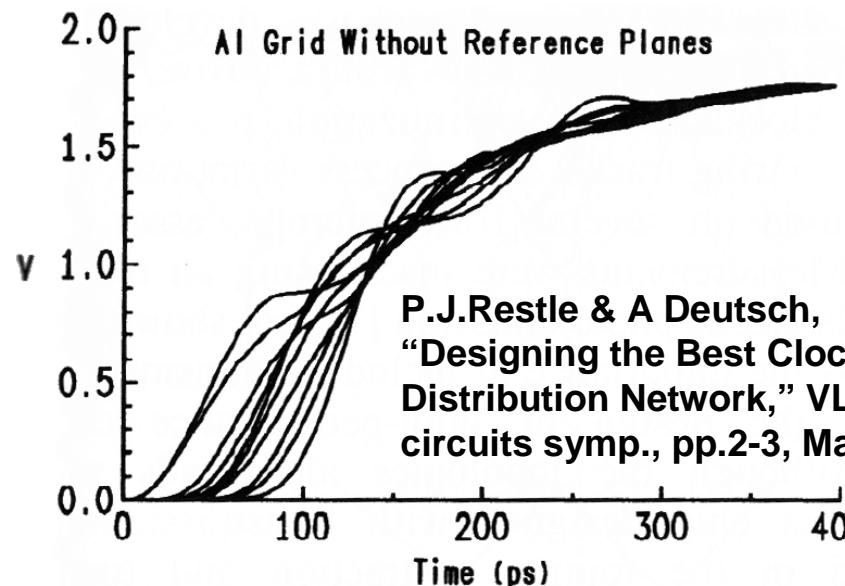
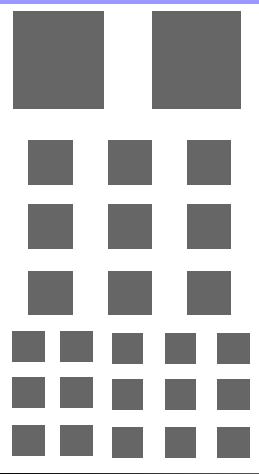
- Now RC effects surmounts LC effects because $R > |j\omega L|$.
- In the future, both of R and ωL increase (R increases more rapid?).
- Exception in low-R lines
- Inductive effects in wide clock lines in a fast processor are claimed to be observed in simulation.
- Clock lines are placed on power plane to reduce inductive effects.

[1] D.A.Priore, "Inductance on Silicon for Sub-micron CMOS VLSI," Symp. on VLSI Circuits, 1993.

Inductive Effects

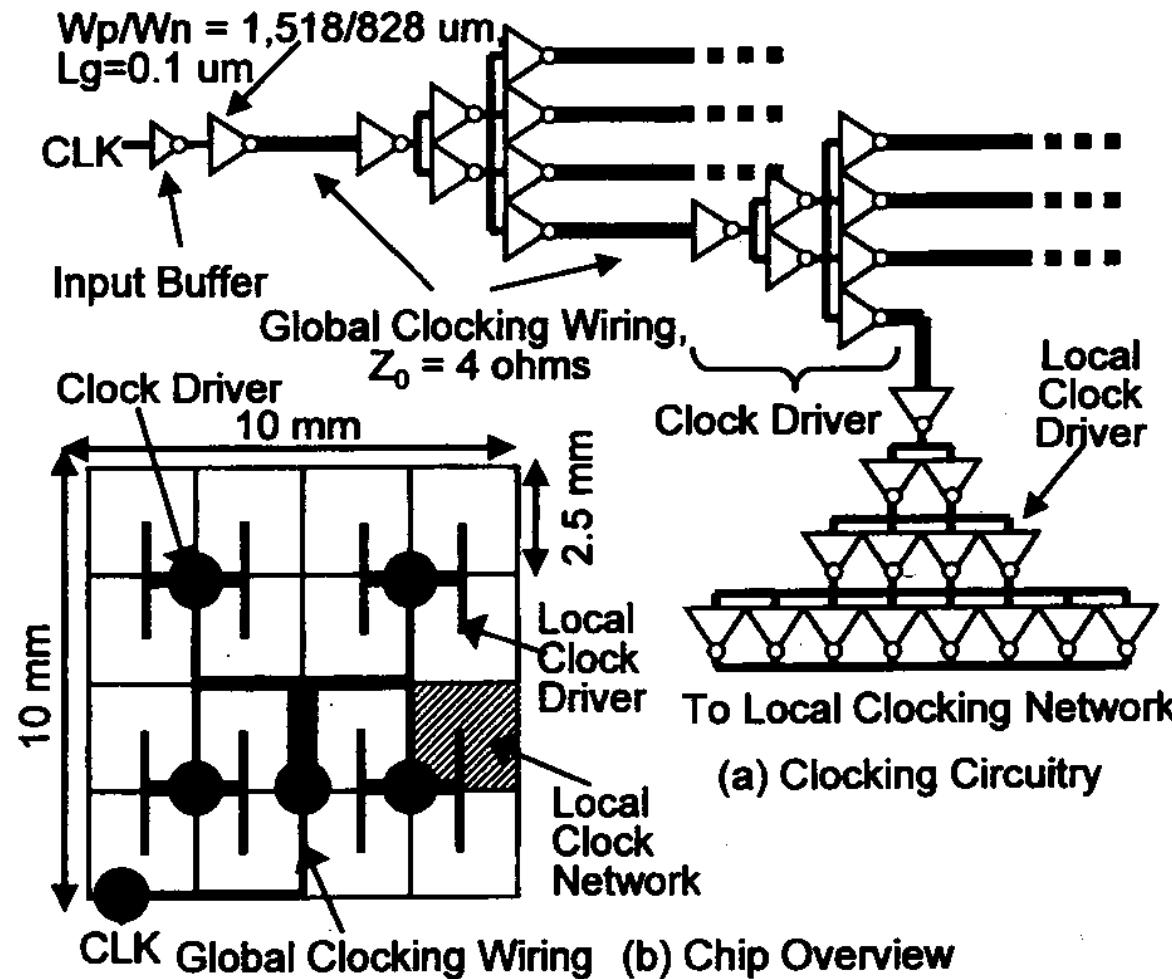


Inductive Effects in Clock Lines



Board design practice is imported in LSI.

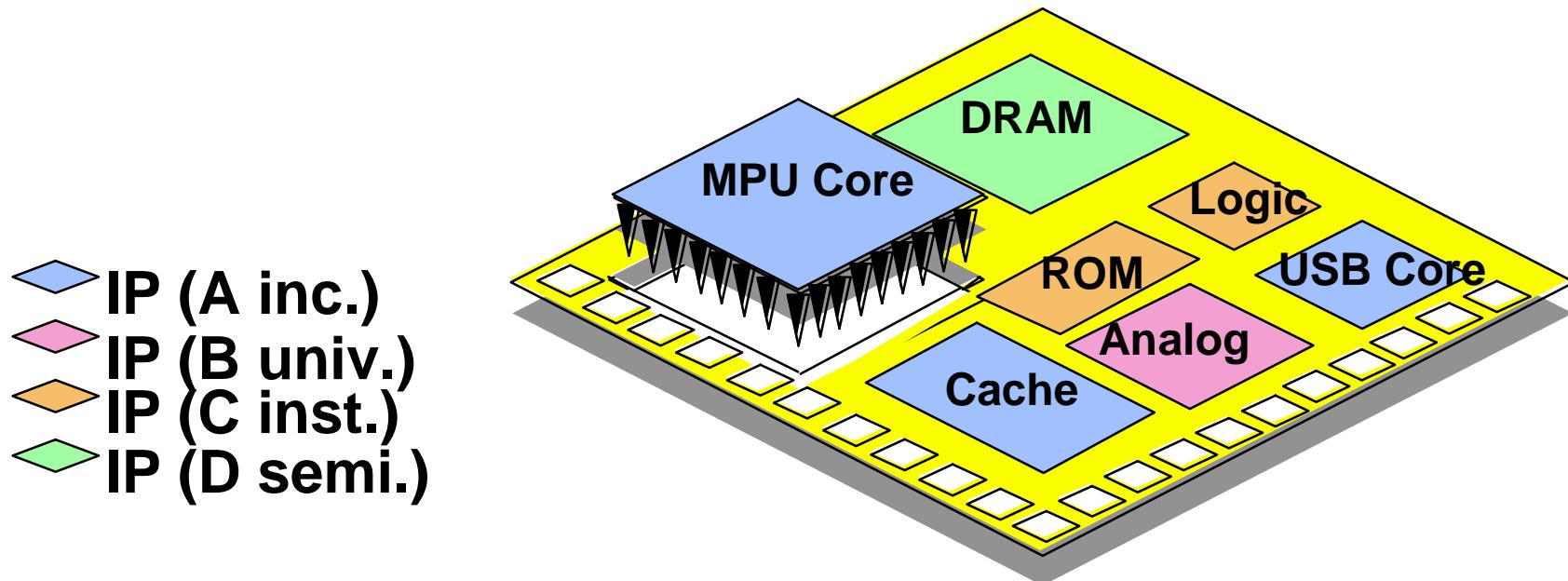
H-tree clock distribution



M.Mizuno, K.Anjo, Y.Sumi, H.Wakabayashi, T.Mogami, T.Horiuchi, M.Yamashina, "On-Chip Multi-GHz Clocking with Transmission Lines," ISSCC, pp.366-367, Feb. 2000

System on a Chip (SoC)

- Re-use and sharing of design
- Design in higher abstraction

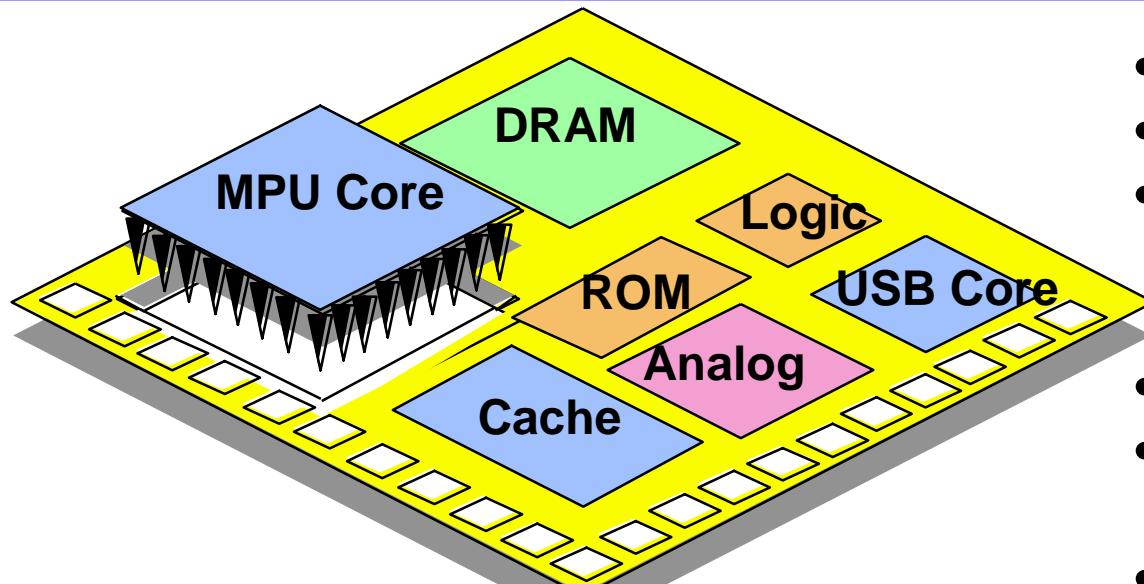


IP ; CPU, DSP, memories, analog, I/O, logic..
HW/FW/SW

Issues in System-on-Chip

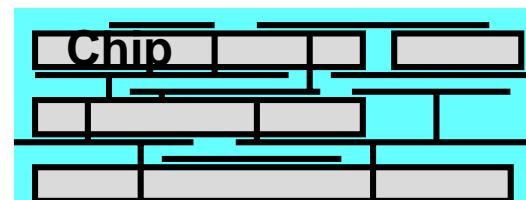
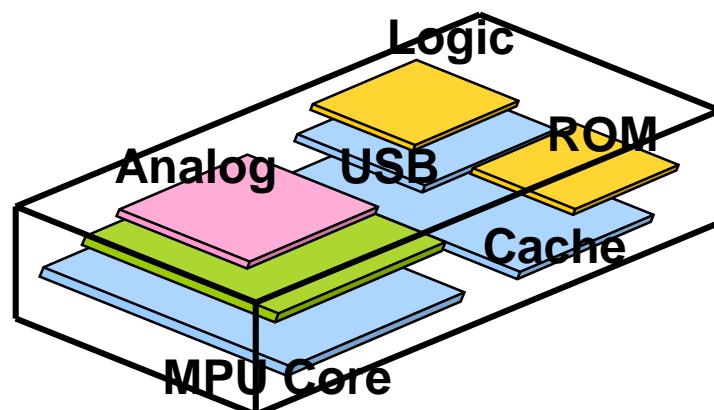
- **Un-distributed IP's (i.e. CPU, DSP of a certain company)**
- **Huge initial investment for masks & development**
- **IP testability, upfront IP test cost**
- **Process-dependent memory IP's**
- **Difficulty in high precision analog IP's due to noise**
- **Process incompatibility with non-Si materials and/or MEMS**

System in Package



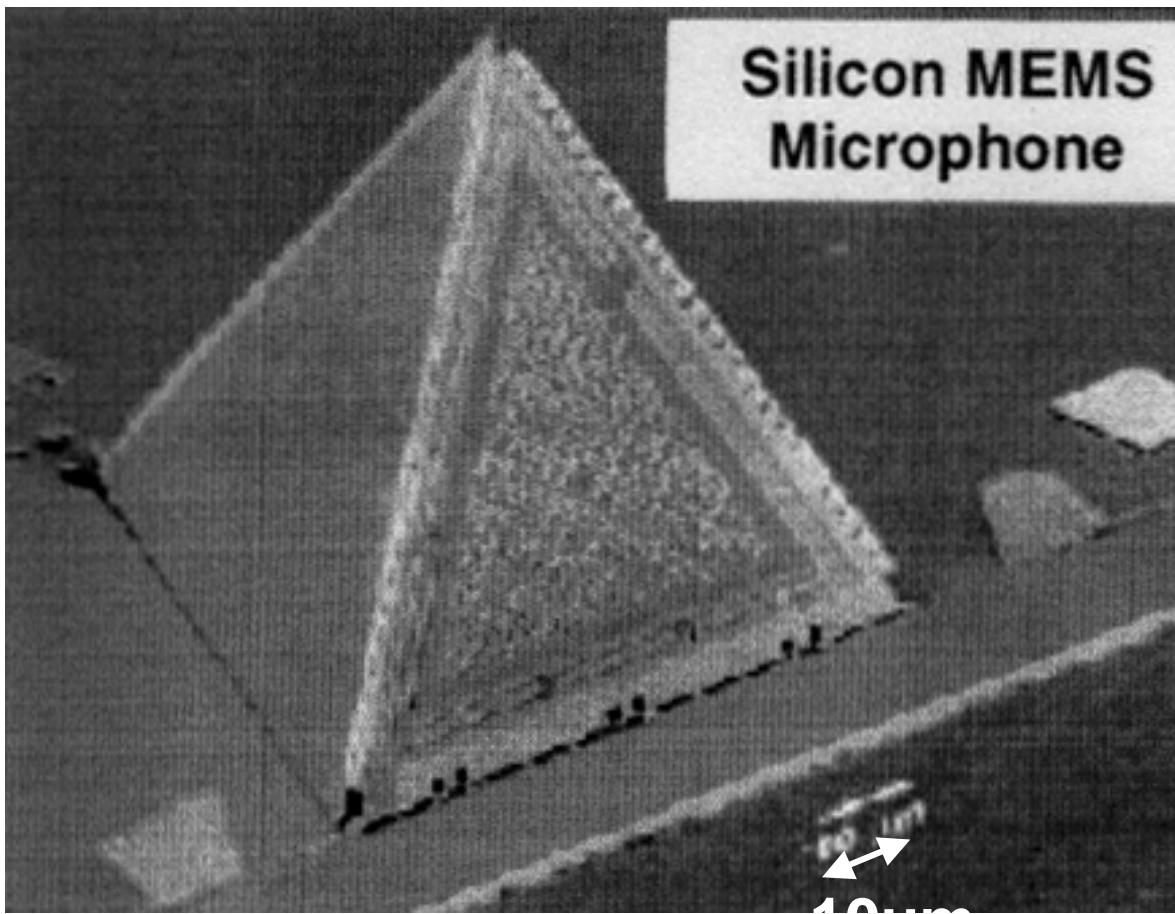
System on a Chip

- Smaller area
 - Shorter interconnect
 - Optimized process for each die (Analog, DRAM, MEMS...)
 - Good electrical isolation
 - Through-chip via
-
- Heat dissipation is an issue



System in Package

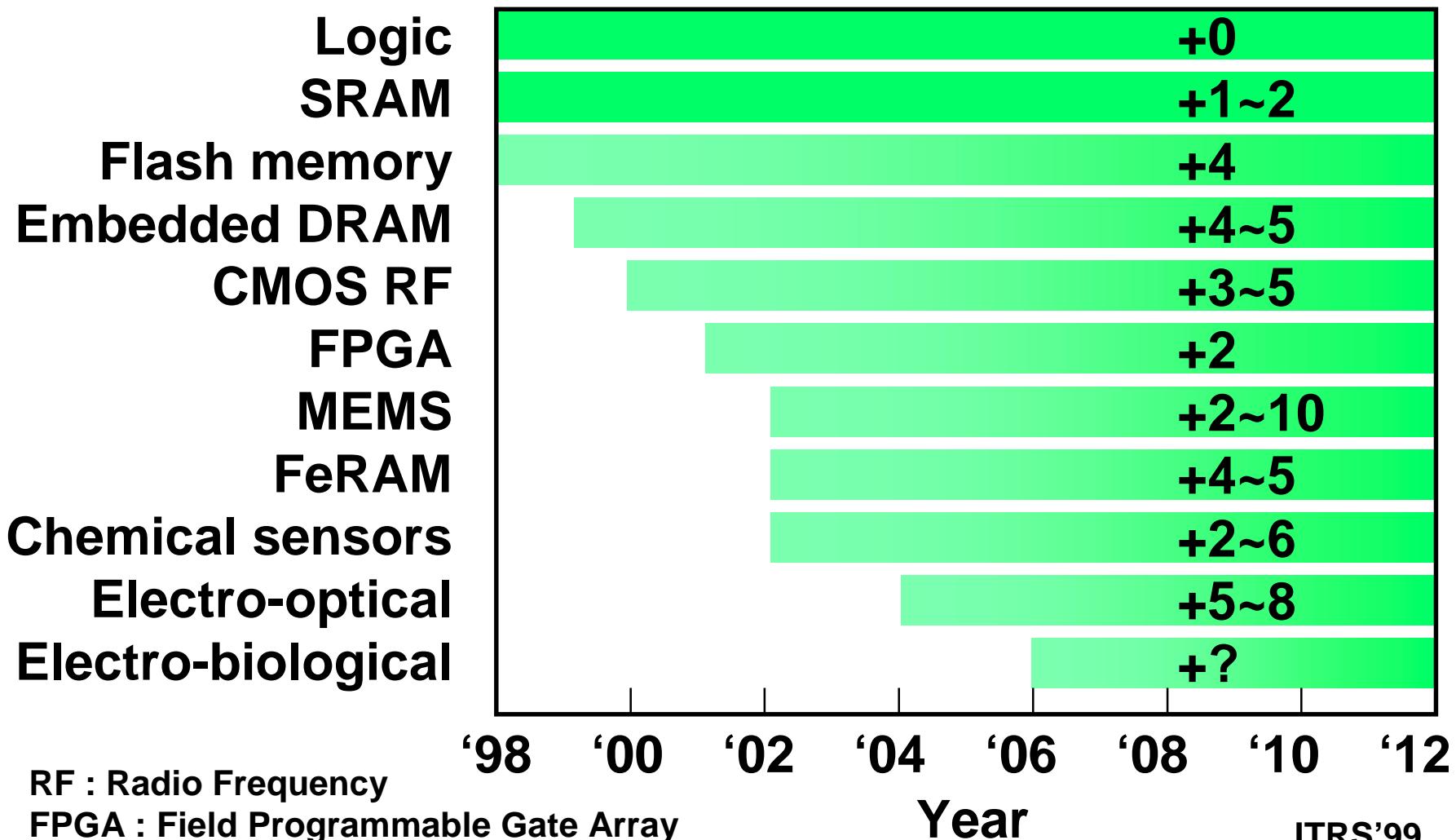
Silicon MEMS microphone



Will soon exceed the performance of the best commercial microphones, yet be inexpensive and potentially integrated with on-chip electronics.

M.Pinto, "Atoms to Applets: Building Systems ICs in the 21st Century," ISSCC, pp.26-30, Feb. 2000.

Technologies integrated on a chip



RF : Radio Frequency

FPGA : Field Programmable Gate Array

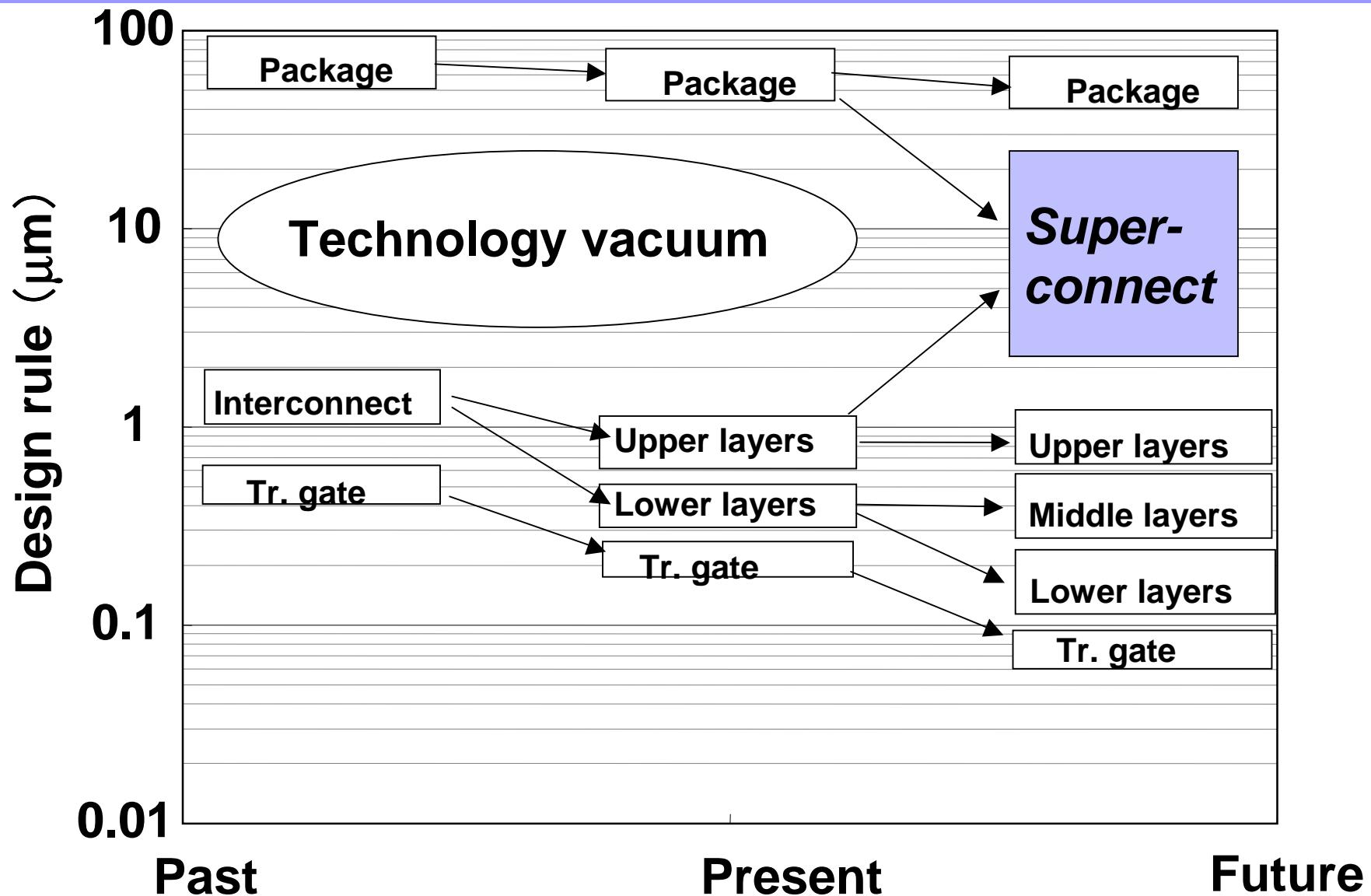
MEMS : Micro Electro Mechanical Systems

FeRAM : Ferroelectric RAM

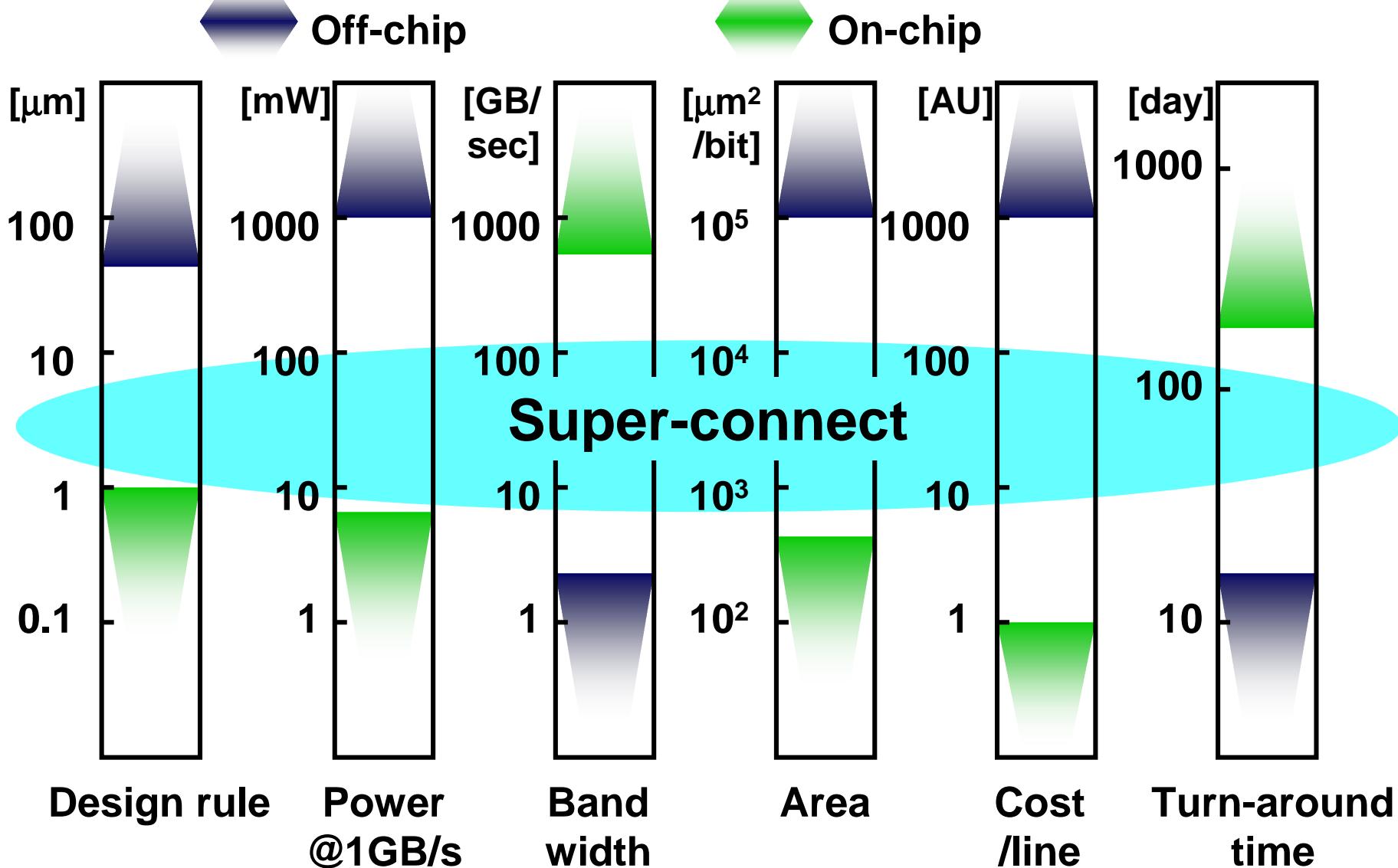
Year

ITRS'99

Super-connect



Super-connect



LSI in 2014

| Year | Unit | 1999 | 2014 | Factor |
|--|-------------------|------|-------|--------|
| Design rule | μm | 0.18 | 0.035 | 0.2 |
| Tr. Density | /cm ² | 6.2M | 390M | 30 |
| Chip size | mm ² | 340 | 900 | 2.6 |
| Tr. Count per chip (μP) | | 21M | 3.6G | 170 |
| DRAM capacity | | 1G | 1T | 1000 |
| Local clock on a chip | Hz | 1.2G | 17G | 14 |
| Global clock on a chip | Hz | 1.2G | 3.7G | 3.1 |
| Power | W | 90 | 183 | 2.0 |
| Supply voltage | V | 1.5 | 0.37 | 0.2 |
| Current | A | 60 | 494.6 | 8 |
| Interconnection levels | | 6 | 10 | 1.7 |
| Mask count | | 22 | 28 | 1.3 |
| Cost / tr. (packaged) | μcents | 1735 | 22 | 0.01 |
| Chip to board clock | Hz | 500M | 1.5G | 3.0 |
| # of package pins | | 810 | 2700 | 3.3 |
| Package cost | cents/pin | 1.61 | 0.75 | 0.5 |

International Technology Roadmap for Semiconductors 1998 update sponsored by the Semiconductor Industry Association in cooperation with European Electronic Component Association (EECA) , Electronic Industries Association of Japan (EIAJ), Korea Semiconductor Industry Association (KSIA), and Taiwan Semiconductor Industry Association (TSIA) , International Technology Roadmap for Semiconductors: 1999 edition. Austin, TX:International SEMATECH, 1999.